

InP HBT Digital ICs and MMICs in the 140-220 GHz band

***Mark Rodwell
University of California, Santa Barbara***

Collaborators

*Z. Griffith, V. Paidi, N. Parthasarathy, C. Sheldon, U. Singiseti
ECE Dept., University of California, Santa Barbara*

*Prof. A. Gossard, Dr. A. Jackson, Mr. J. English
Materials Dept., University of California, Santa Barbara*

*M. Urteaga, R. Pierson, P. Rowell, B. Brar
Rockwell Scientific Company*

*X. M. Fang, D. Lubyshev, Y. Wu, J. M. Fastenau, W.K. Liu
International Quantum Epitaxy, Inc.*

*Lorene Samoska, Andy Fung
Jet Propulsion Laboratories*

*S. Lee, N. Nguyen, and C. Nguyen
Global Communication Semiconductors*

Sponsors

*J. Zolper, S. Pappert, M. Rosker
DARPA (TFAST, ABCS, SMART)*

*D. Purdy, I. Mack, M. Yoder
Office of Naval Research*

What could we do with 100-350 GHz integrated circuits ?

Optical Fiber Transmission

40 Gb/s: InP and SiGe ICs commercially available

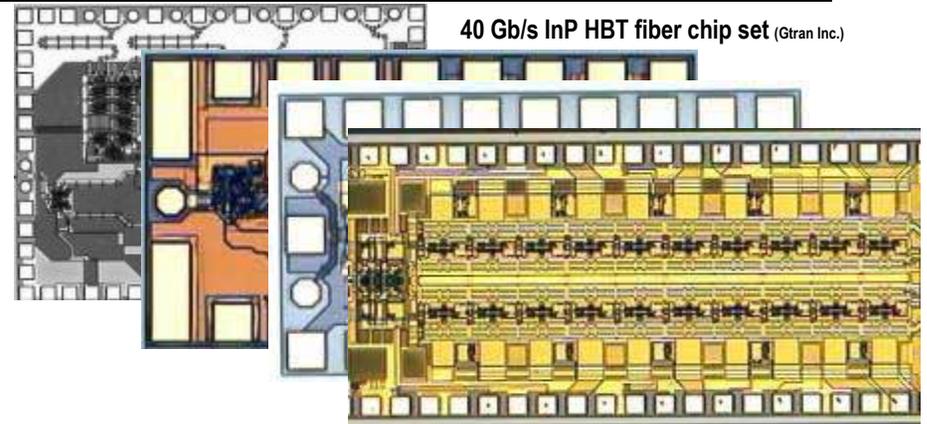
80 & 160 Gb/s is feasible

80-160 Gb/s InP ICs now clearly feasible

~100 GHz modulators demonstrated

100 + GHz photodiodes are easy

challenge: fiber dispersion



Radio-wave Transmission / Radar / Imaging

65-80 GHz, 120-160 GHz, 220-300 GHz

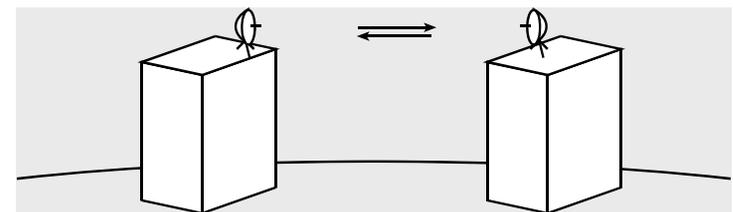
100 Gb/s transmission over 1 km in heavy rain

300 GHz imaging for foul-weather aviation

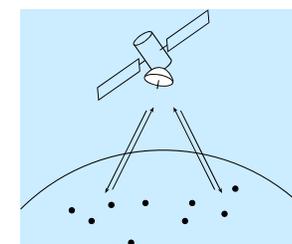
science

spectroscopy, radio astronomy

250 GHz digital radio: 100 Gb/s over 1 km in heavy rain



mm-wave sensor networks



300 GHz imaging



Mixed-Signal ICs for Military Radar/Comms

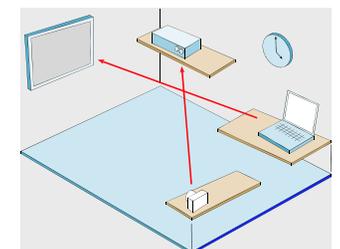
direct digital frequency synthesis, ADCs, DACs

high resolution at very high bandwidths sought

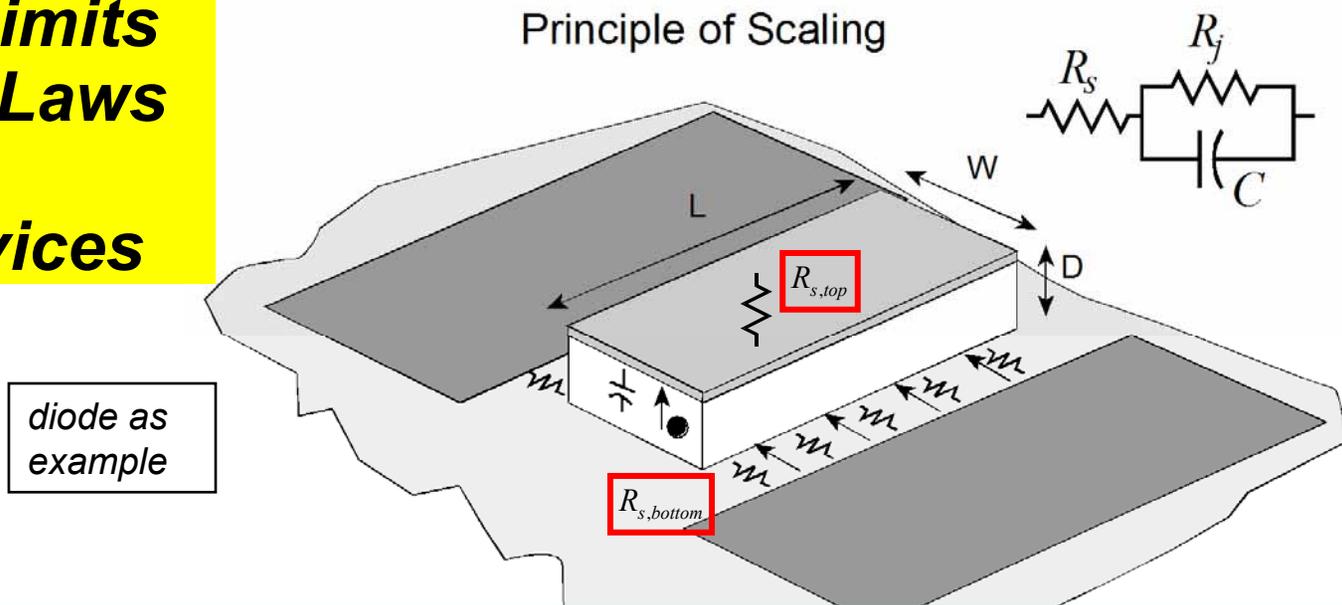
Why develop transistors for mm-wave & sub-mm-wave applications ?

→ compact ICs supporting complex high-frequency systems.

Gb/s Wireless Home Networks

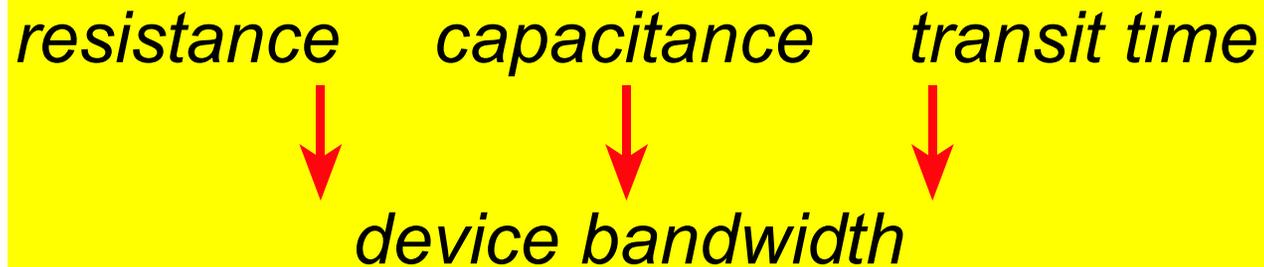


Frequency Limits and Scaling Laws of (most) Electron Devices



contributing parameters	time constant	to double bandwidth
transit time	$\tau \propto D / v_{electron}$	reduce D by 2:1
$C \propto WL / D$ $R_{s,bottom} \propto 1 / L$	$R_{s,bottom} C \propto W / D$	reduce W by 4:1
$C \propto WL / D$ $R_{s,top} \propto \rho_{contact} / WL$	$R_{s,top} C \propto \rho_{contact} / D$	reduce $\rho_{contact}$ by 4:1 use Schottky: $\rho_{contact} = 0$ use flared contact: $R_{s,top} L \sim \rho_c \ln(1/W)$
$C \propto WL / D$ $R_{junction} \propto kT / qI$	$R_{junction} C \propto WL / ID$ $\propto 1 / JD$	increase J by 4:1
space - charge limited J		$J_{max} \propto (V + \phi) v_{electron} / D^2$, increases 4:1

R/C/ τ Limits the Bandwidth of (most) Electron Devices



applies to:

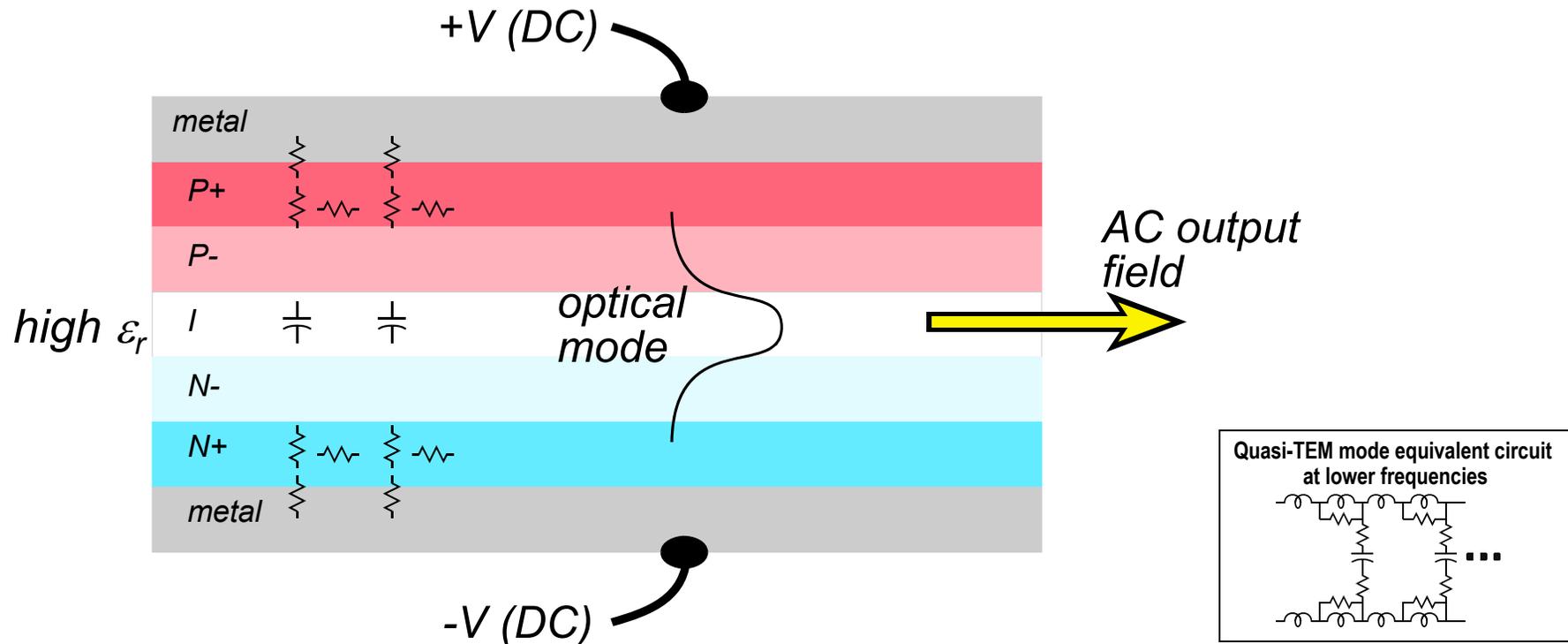
*bipolar transistors, field-effect transistors, Schottky diodes
RTDs, photomixers, photodiodes*

Applies whenever AC signals are removed through Ohmic contacts

Effective THz devices

***must minimize, eliminate, or circumvent
contact resistance, capacitance, & transit time***

Why aren't semiconductor lasers $R/C/\tau$ limited ?



**dielectric waveguide mode confines AC field
away from resistive bulk and contact regions.**

AC signal is not coupled through electrical contacts

dielectric mode confinement is harder at lower frequencies

Diode & Transistor Integrated Circuits to ~ 1 THz

10-nm to 100-nm electron drift devices:

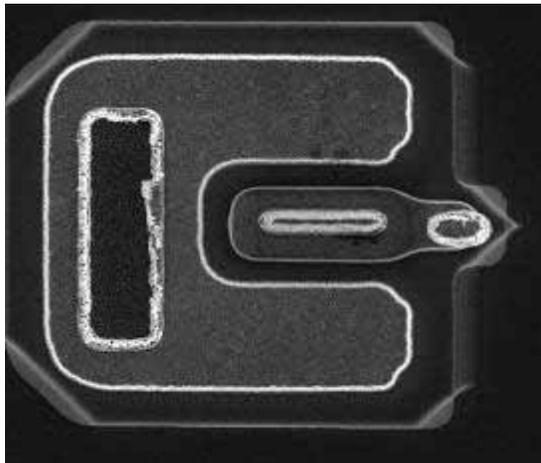
***100 nm-generation InP DHBTs
signal generation with power to ~500 GHz***

***< 30 nm-generation InP HEMTs
30 nm devices now get ~600 GHz f_t
→ low noise figure at 300 GHz***

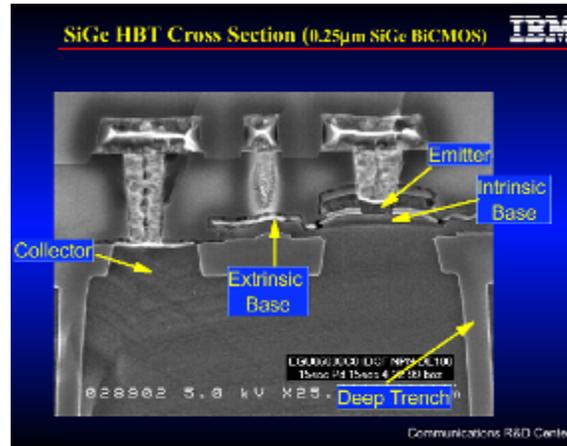
***<50 nm-generation InP or GaAs Schottky mixer diodes
many THz RC and transit time frequencies***

And Silicon VLSI for applications below ~150 GHz !

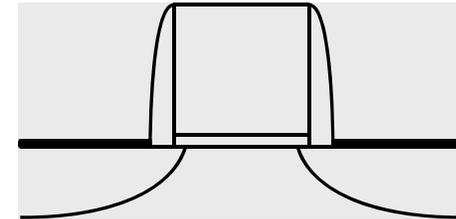
Fast IC Technologies



InP HBT: 500 nm emitter
455 GHz f_t / 485 GHz f_{max}
~4 V breakdown
150 GHz static dividers
178 GHz amplifiers



SiGe HBT: 130 nm emitter
300 GHz f_t / 350 GHz f_{max}
96 GHz static dividers
77 GHz amplifiers
150 GHz push-push VCO- 75 GHz fundamental



CMOS: 90 nm node:
~200 GHz f_t / 250 GHz f_{max}
60 GHz 2:1 mux
91 GHz amplifiers

InP HBTs:

450 GHz bandwidth at 500 nm scaling

Potential for much wider bandwidths at 100 nm scaling

We design HBTs for fast logic, not for high f_τ & f_{max}

Gate Delay Determined by :

Depletion capacitance charging through the logic swing

$$\left(\frac{\Delta V_{LOGIC}}{I_C} \right) (C_{cb} + C_{be,depletion})$$

Depletion capacitance charging through the base resistance

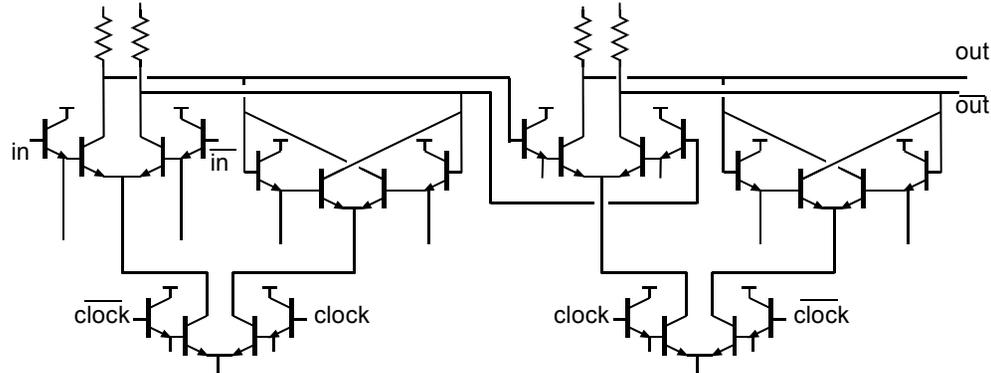
$$R_{bb} (C_{cbi} + C_{be,depletion})$$

Supplying base + collector stored charge through the base resistance

$$R_{bb} (\tau_b + \tau_c) \left(\frac{I_C}{\Delta V_{LOGIC}} \right)$$

The logic swing must be at least

$$\Delta V_{LOGIC} > 4 \cdot \left(\frac{kT}{q} + R_{ex} I_c \right)$$



$(\tau_b + \tau_c)$ typically 10 - 25% of total delay;
Delay not well correlated with f_τ

$(\Delta V_{LOGIC} / I_C) (C_{cb} + C_{be,depl})$ is 55% - 80% of total.

High (I_C / C_{cb}) is a key HBT design objective.

$$J_{max, Kirk} = 2\varepsilon\bar{v}_{electron} (V_{ce, operating} + V_{ce, full depletion}) / T_c^2$$

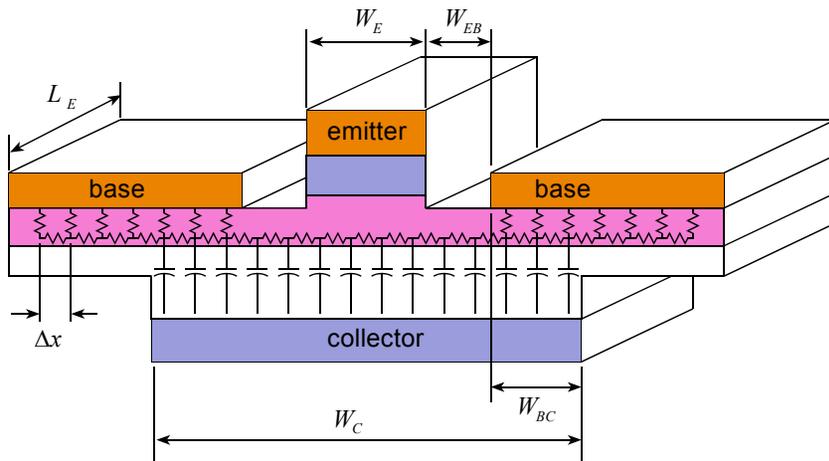
$$\Rightarrow \frac{C_{cb} \Delta V_{LOGIC}}{I_C} = \frac{\Delta V_{LOGIC}}{2V_{CE, min}} \left(\frac{A_{collector}}{A_{emitter}} \right) \left(\frac{T_c}{2\bar{v}_{electron}} \right)$$

R_{ex} must be very low for low ΔV_{logic} at high J

Bipolar Transistor Scaling Laws & Scaling Roadmaps

Scaling Laws:
design changes required
to double transistor bandwidth

key device parameter	required change
collector depletion layer thickness	decrease 2:1
base thickness	decrease 1.414:1
emitter junction width	decrease 4:1
collector junction width	decrease 4:1
emitter resistance per unit emitter area	decrease 4:1
current density	increase 4:1
base contact resistivity (if contacts lie above collector junction)	decrease 4:1
base contact resistivity (if contacts do not lie above collector junction)	unchanged



InP Technology Roadmap
40 / 80 / 160 Gb/s digital clock rate

Parameter	Gen. 1	Gen. 2	Gen. 3
MS-DFF speed	60 GHz	121 GHz	260 GHz
Emitter Width	1 μm	0.8 μm	0.3 μm
Parasitic Resistivity	50 $\Omega\text{-}\mu\text{m}^2$	20 $\Omega\text{-}\mu\text{m}^2$	5 $\Omega\text{-}\mu\text{m}^2$
Base Thickness	400 \AA	400 \AA	300 \AA
Doping	5 $10^{19}/\text{cm}^2$	7 $10^{19}/\text{cm}^2$	7 $10^{19}/\text{cm}^2$
Sheet resistance	750 Ω	700 Ω	700 Ω
Contact resistance	150 $\Omega\text{-}\mu\text{m}^2$	20 $\Omega\text{-}\mu\text{m}^2$	20 $\Omega\text{-}\mu\text{m}^2$
Collector Width	3 μm	1.6 μm	0.7 μm
Collector Thickness	3000 \AA	2000 \AA	1000 \AA
Current Density	1 $\text{mA}/\mu\text{m}^2$	2.3 $\text{mA}/\mu\text{m}^2$	12 $\text{mA}/\mu\text{m}^2$
$A_{\text{collector}}/A_{\text{emitter}}$	4.55	2.6	2.9
f_T	170 GHz	248 GHz	570 GHz
f_{max}	170 GHz	411 GHz	680 GHz
I_E/L_E	1 $\text{mA}/\mu\text{m}$	1.9 $\text{mA}/\mu\text{m}$	3.7 $\text{mA}/\mu\text{m}$
τ_f	0.67 ps	0.50 ps	0.22 ps
C_{cb}/I_c	1.7 ps/V	0.62 ps/V	0.26 ps/V
$C_{cb} \Delta V_{\text{logic}} / I_c$	0.5 ps	0.19 ps	0.09 ps
$R_{bb}/(\Delta V_{\text{logic}} / I_c)$	0.8	0.68	0.99
$C_{je}(\Delta V_{\text{logic}} / I_c)$	1.7 ps	0.72 ps	0.15 ps
$R_{ex}/(\Delta V_{\text{logic}} / I_c)$	0.1	0.15	0.17

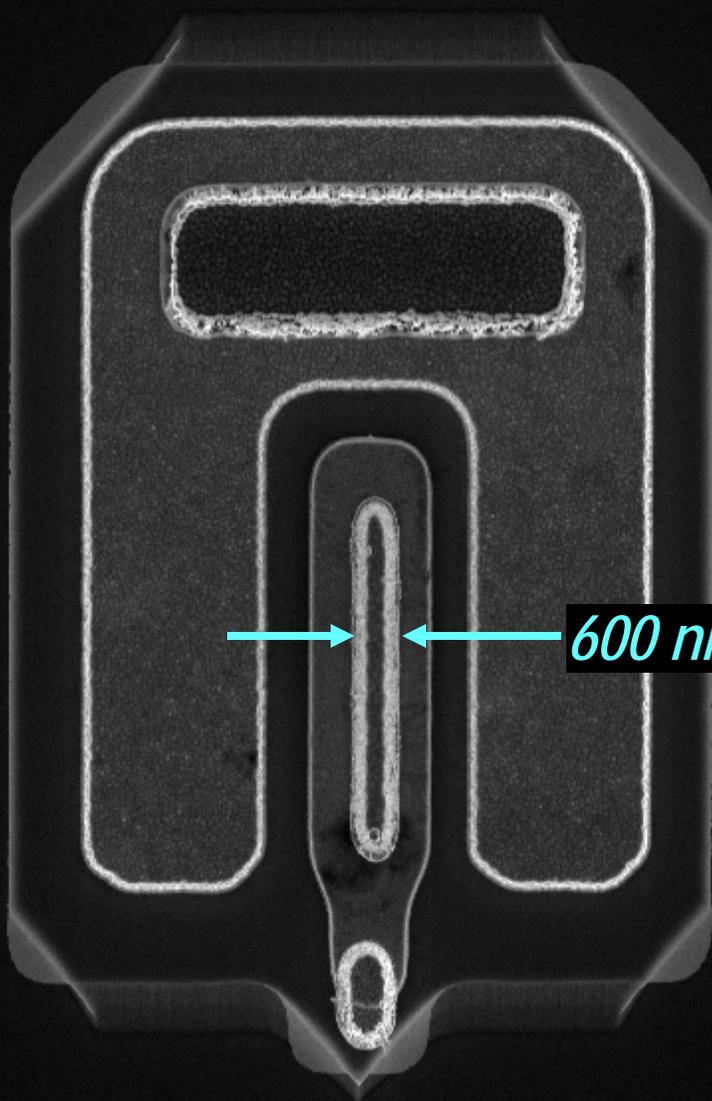
key figures of merit for logic speed

Key scaling challenges →
emitter & base contact resistivity
current density → device heating
collector-base junction width scaling
& Yield !

Transistors & ICs at 500-600 nm Scaling Generation

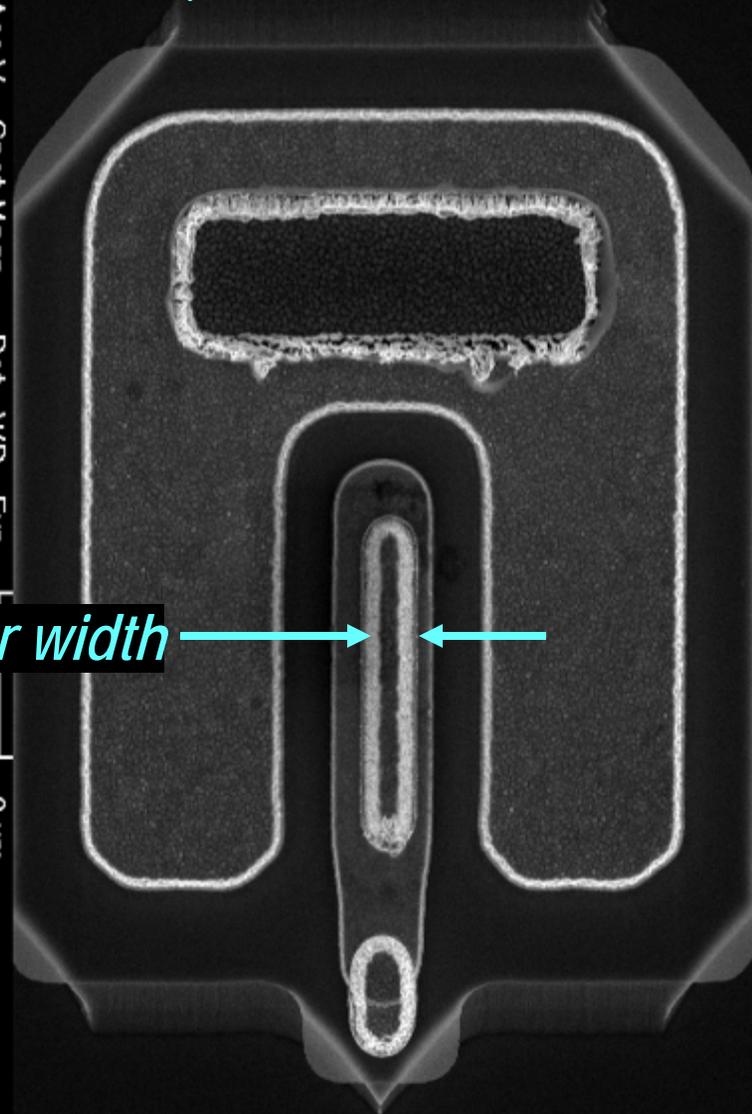
1.7 μm base-collector mesa

V Spot Magn Det WD Exp
KV 3.0 6500x TLD 6.8 1
DHB T19b, r14, no passivation
5 μm



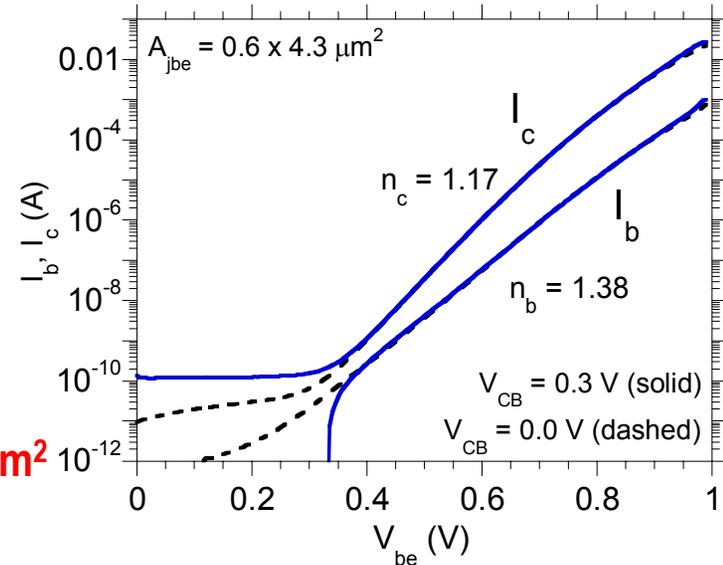
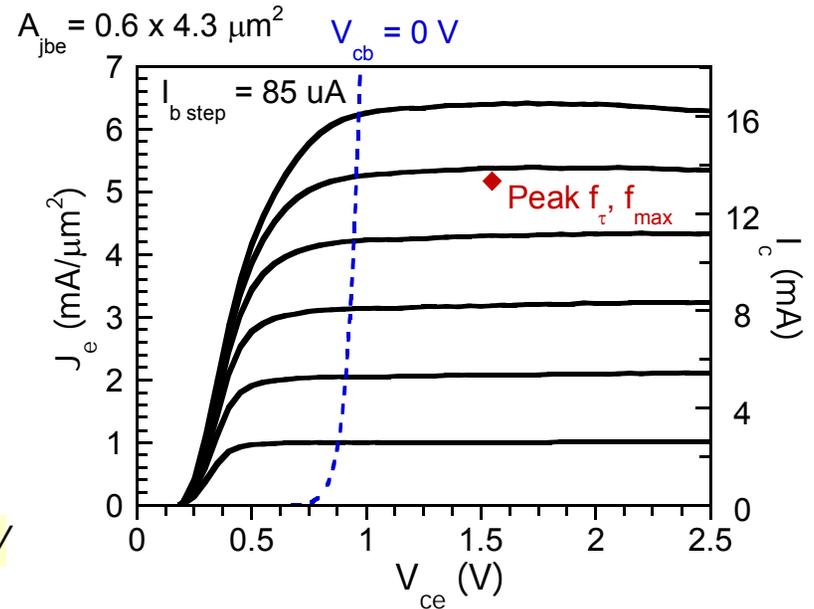
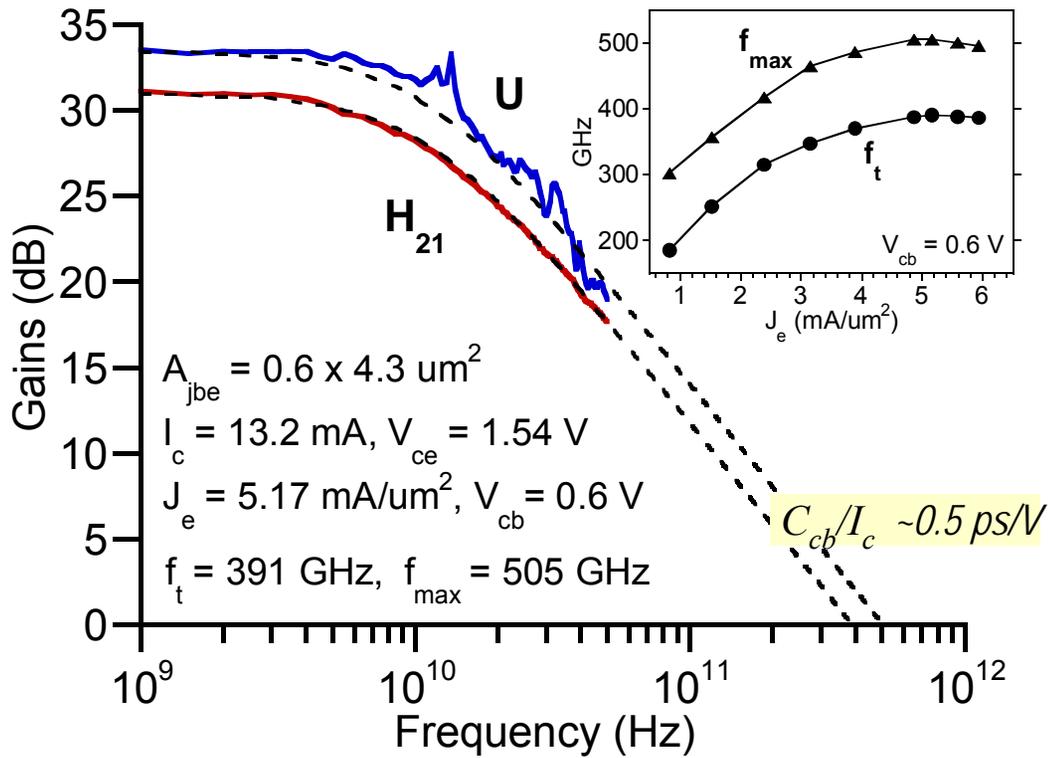
1.3 μm base-collector mesa

Acc. V Spot Magn Det WD Exp
5.00 KV 3.0 8000x TLD 6.8 1
DHB T19b, r14, no passivation
2 μm



600 nm emitter width

InP DHBT: 600 nm lithography, 150 nm thick collector, 30 nm thick base



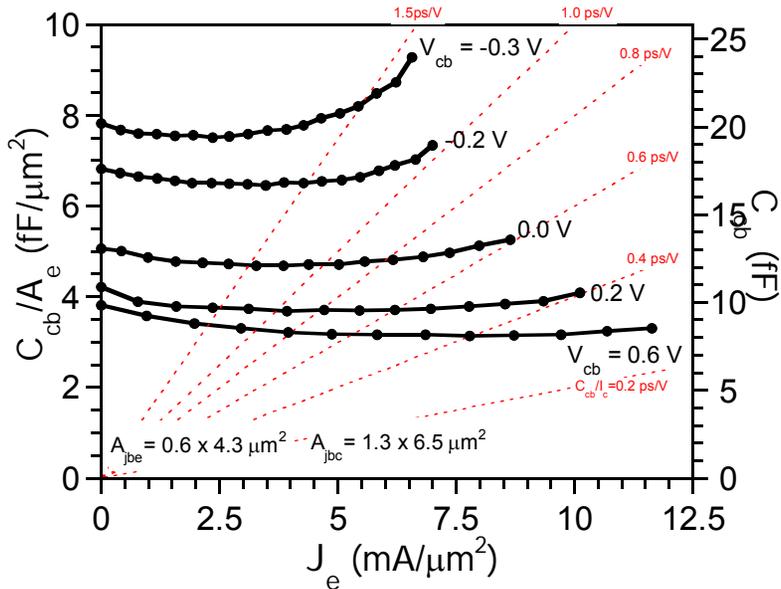
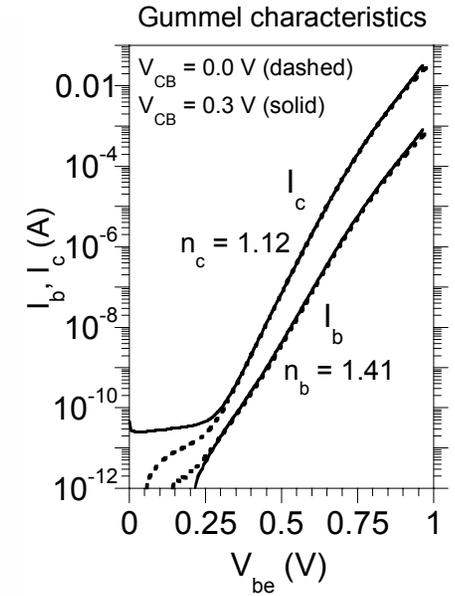
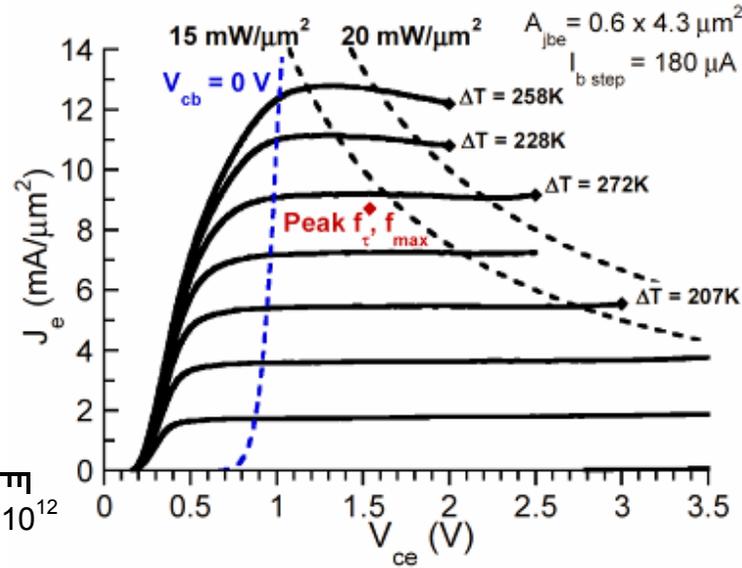
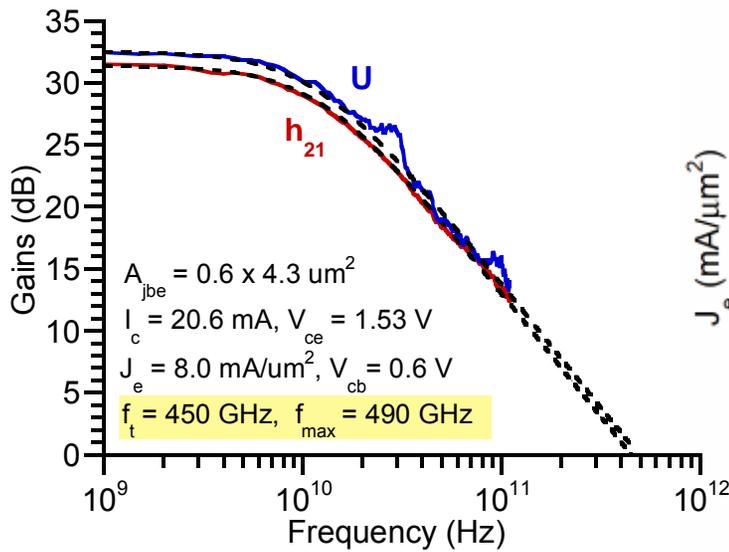
Average $\beta \approx 36, V_{BR,CEO} = 5.1 \text{ V} (I_c = 50 \text{ } \mu\text{A})$

Emitter contact (from RF extraction), $R_{cont} = 10.1 \text{ } \Omega \cdot \mu\text{m}^2$

Base (from TLM) : $R_{sheet} = 564 \text{ } \Omega/\text{sq}, R_{cont} = 9.6 \text{ } \Omega \cdot \mu\text{m}^2$

Collector (from TLM) : $R_{sheet} = 11.9 \text{ } \Omega/\text{sq}, R_{cont} = 5.4 \text{ } \Omega \cdot \mu\text{m}^2$

InP DHBT: 600 nm lithography, 120 nm thick collector, 30 nm thick base



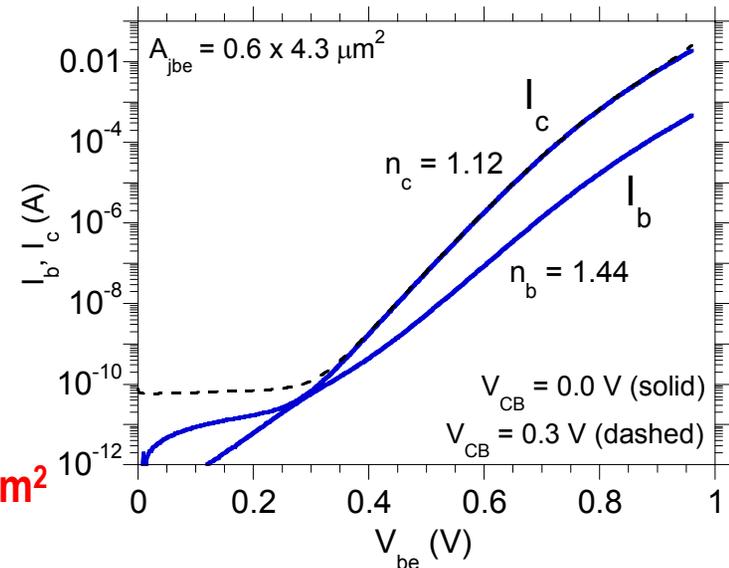
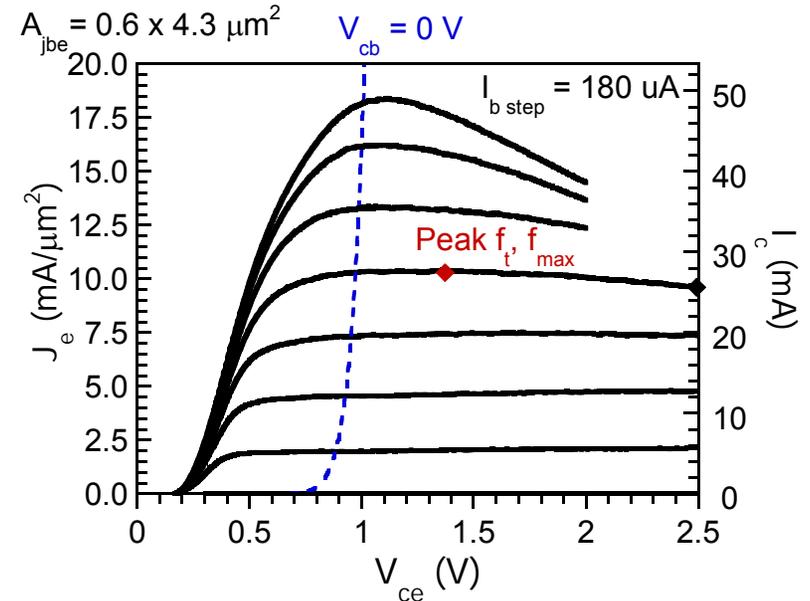
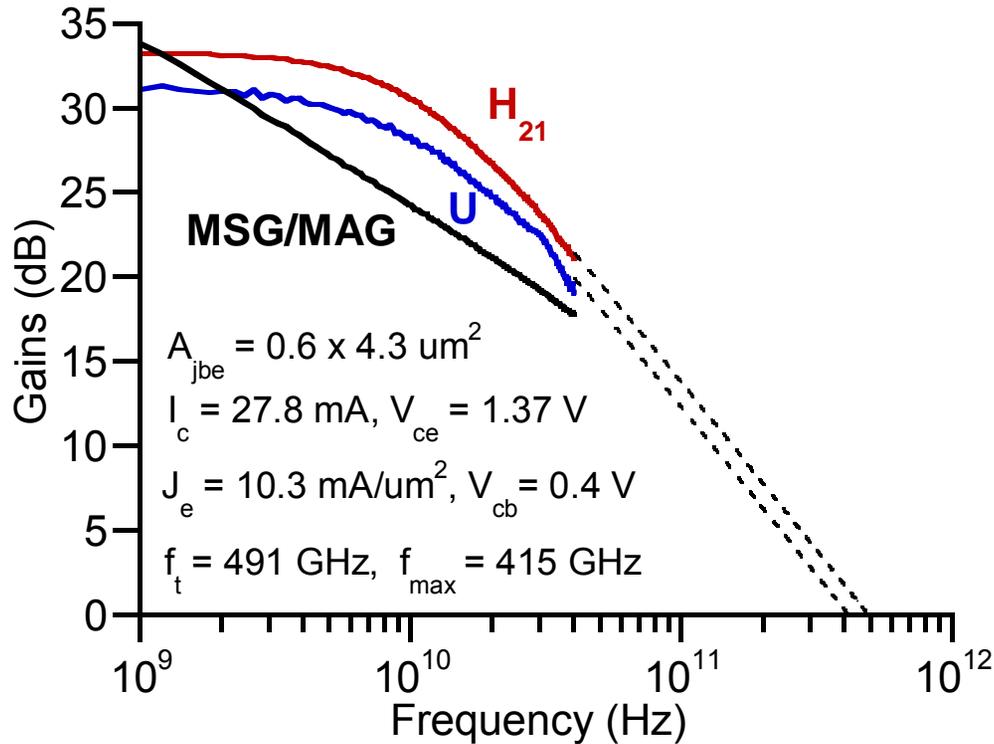
$\beta \approx 40, V_{BR,CEO} = 3.9 \text{ V}.$

Emitter contact $R_{cont} < 10 \Omega \cdot \mu\text{m}^2$

Base : $R_{sheet} = 610 \Omega/\text{sq}, R_{cont} = 4.6 \Omega \cdot \mu\text{m}^2$

Collector : $R_{sheet} = 12.1 \Omega/\text{sq}, R_{cont} = 8.4 \Omega \cdot \mu\text{m}^2$

InP DHBT: 600 nm lithography, 100 nm thick collector, 30 nm thick base



Summary of device parameters—

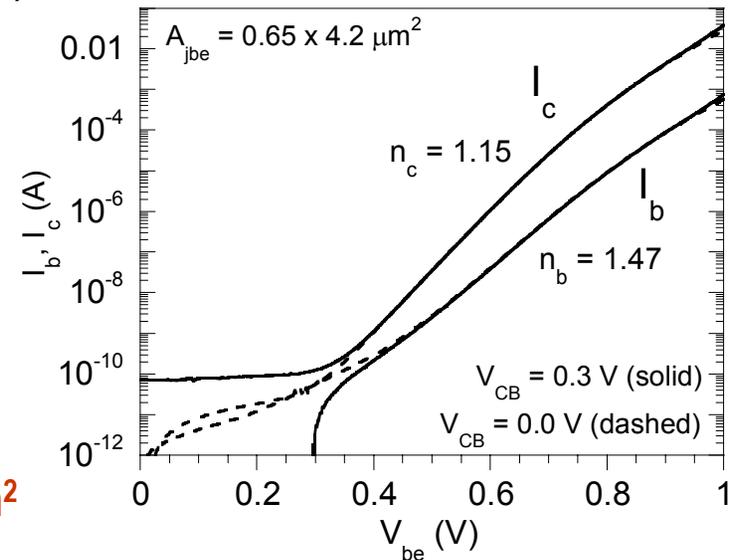
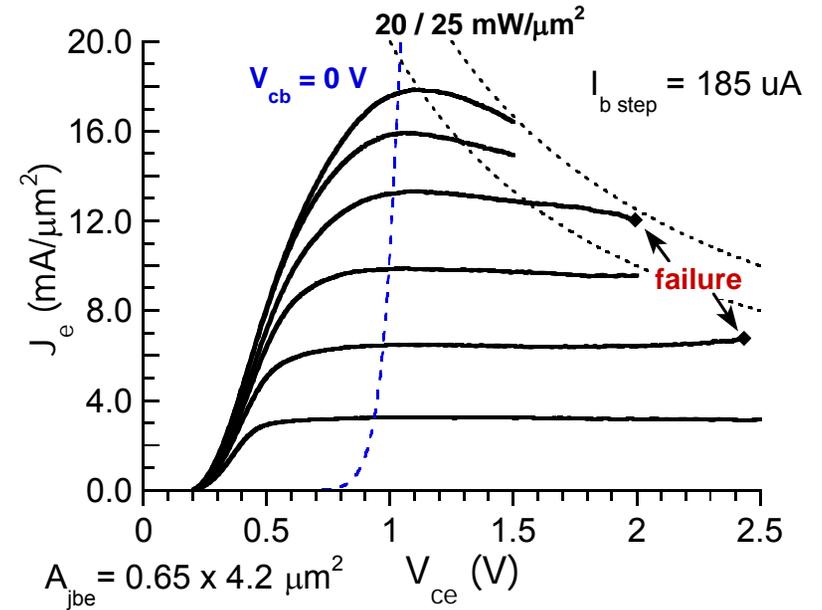
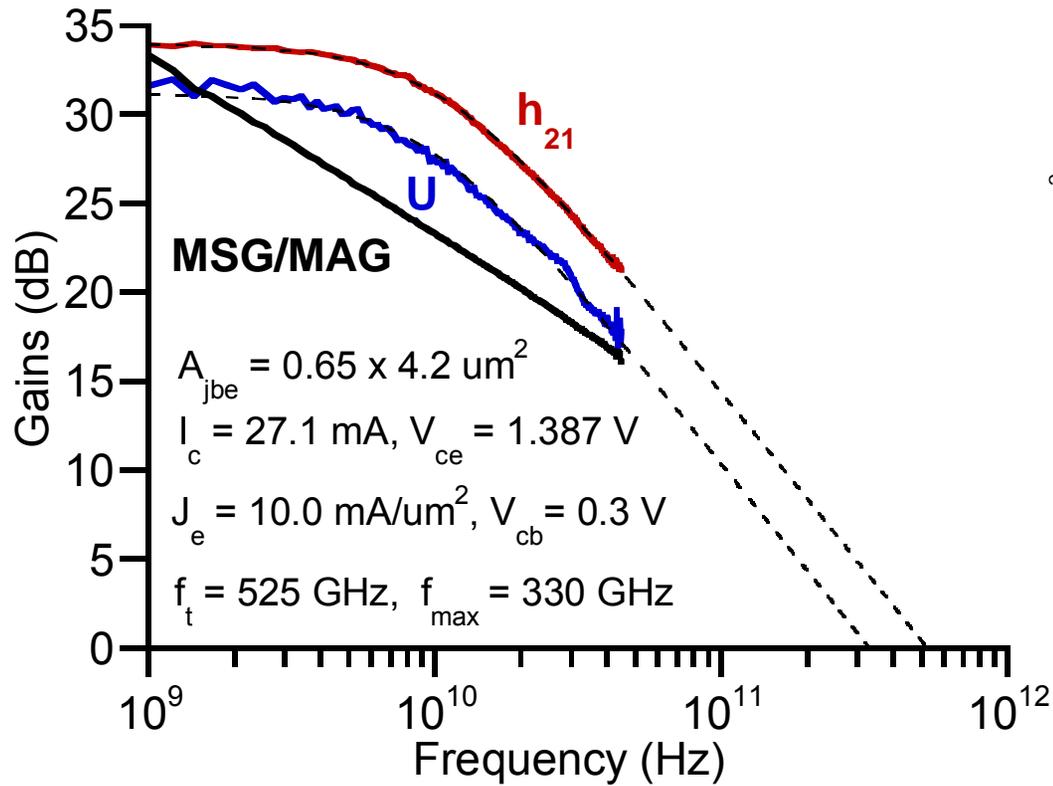
Average $\beta \approx 40$, $V_{BR,CEO} = 3.1 \text{ V}$ ($I_c = 50 \mu\text{A}$)

Emitter contact (from RF extraction), $R_{cont} \approx 7.8 \Omega \cdot \mu\text{m}^2$

Base (from TLM): $R_{sheet} = 629 \Omega/\text{sq}$, $R_{cont} = 6.2 \Omega \cdot \mu\text{m}^2$

Collector (from TLM): $R_{sheet} = 12.9 \Omega/\text{sq}$, $R_{cont} = 4.0 \Omega \cdot \mu\text{m}^2$

InP DHBT: 600 nm lithography, 75 nm thick collector, 25 nm thick base



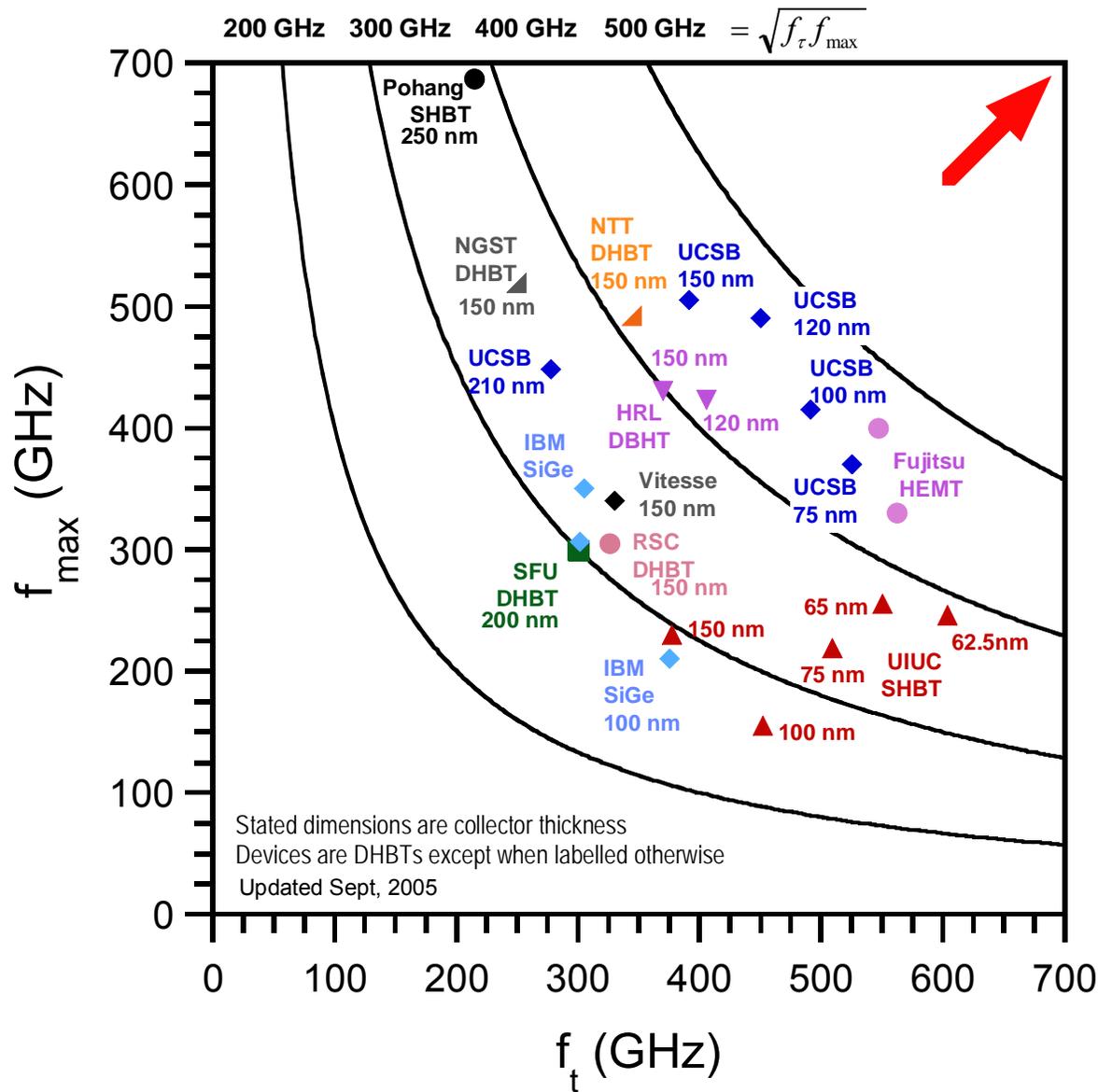
Average $\beta \approx 50$, $BV_{CEO} = 3.1 \text{ V}$, $BV_{CBO} = 3.4 \text{ V}$ ($I_c = 50 \mu\text{A}$)

Emitter contact (from RF extraction), $R_{cont} \approx \text{TBD } \Omega \cdot \mu\text{m}^2$

Base (from TLM): $R_{sheet} = 805 \Omega/\text{sq}$, $R_{cont} = 16 \Omega \cdot \mu\text{m}^2$

Collector (from TLM): $R_{sheet} = 12.0 \Omega/\text{sq}$, $R_{cont} = 4.7 \Omega \cdot \mu\text{m}^2$

Summary of published HBT performance



popular metrics :

$$(f_t + f_{max}) / 2$$

$$\sqrt{f_t f_{max}}$$

$$(1/f_t + 1/f_{max})^{-1}$$

better metrics :

power amplifiers :

PAE,
 associated gain,
 $mW/\mu m$

low noise amplifiers :

F_{min} ,
 associated gain,
 associated DC power

digital :

f_{clock} , hence

$$(C_{cb} \Delta V / I_c),$$

$$(R_{ex} I_c / \Delta V),$$

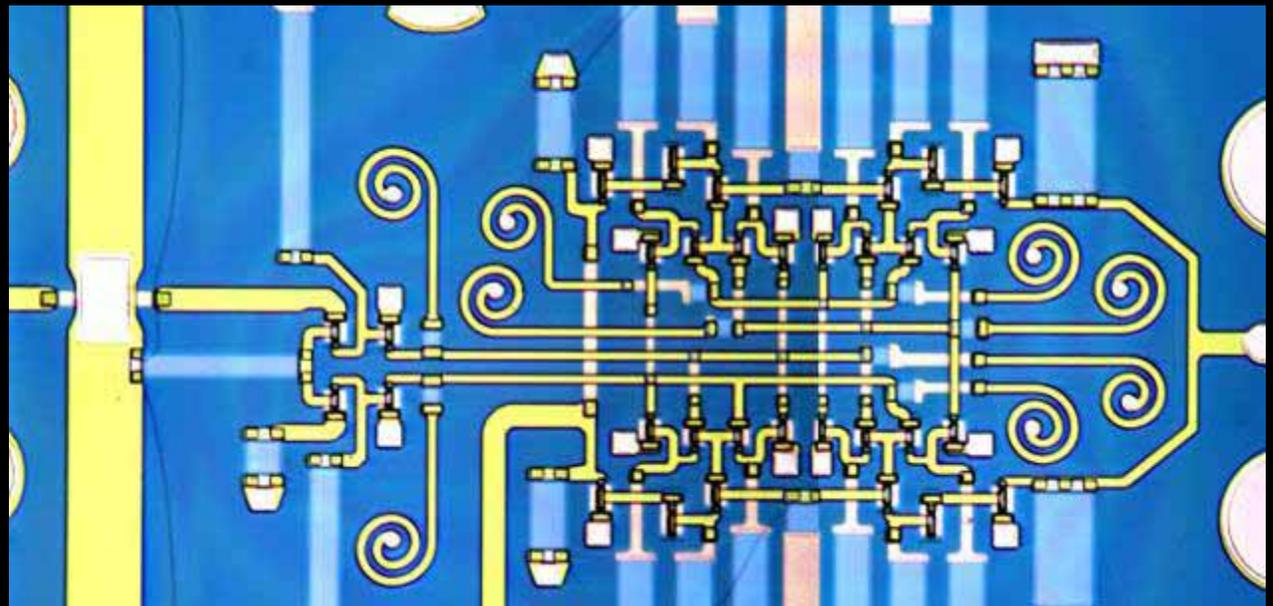
$$(R_{bb} I_c / \Delta V),$$

$$(\tau_b + \tau_c)$$

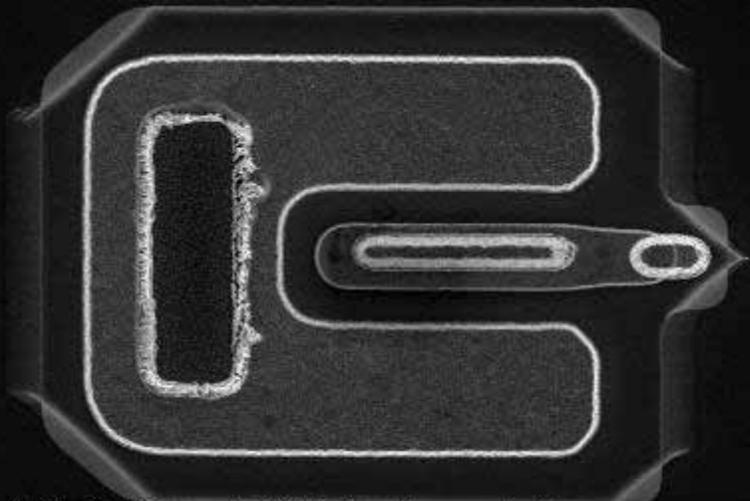
UCSB results are @ 600 nm; further progress requires scaling to 250 nm

Digital circuits: towards 200 GHz clock rate

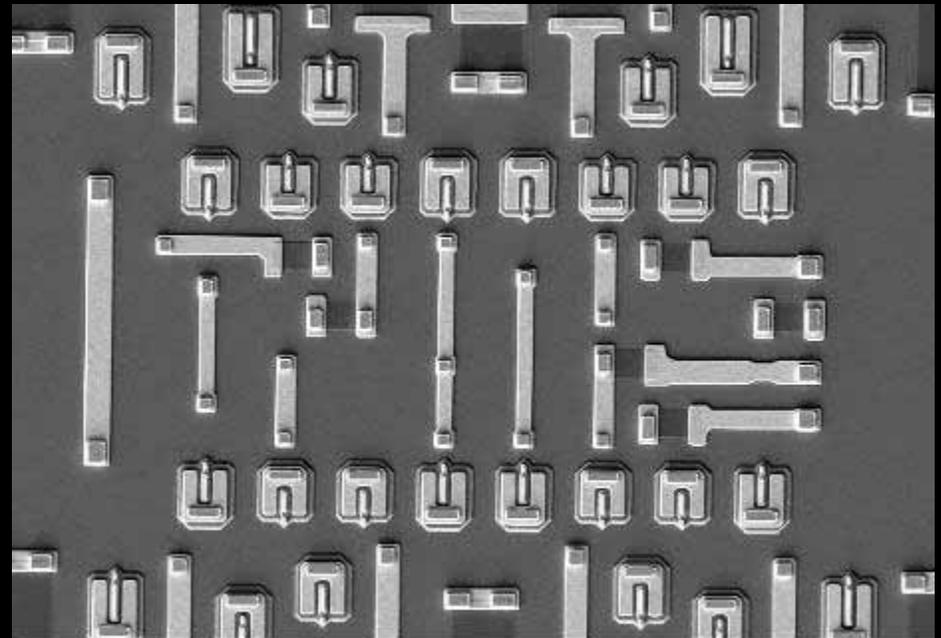
142 GHz latch from NNIN @ UCSB,
150 GHz ICs from UCSB/GSC/RSC
200 GHz is the next goal



underlying technology:
400-500 GHz InP transistors



Acc.V Spot Magn Det WD Exp | 2 μ m
5.00 kV 3.0 8000x TLD 6.8 1 DHBT19b, r14, no passivation



Acc.V Spot Magn Det WD Exp | 50 μ m
10.0 kV 3.0 1500x SE 6.6 1 r16-DHBT25, E0.5 B0.3, L4.25

Static Frequency Divider: Standard Digital Benchmark

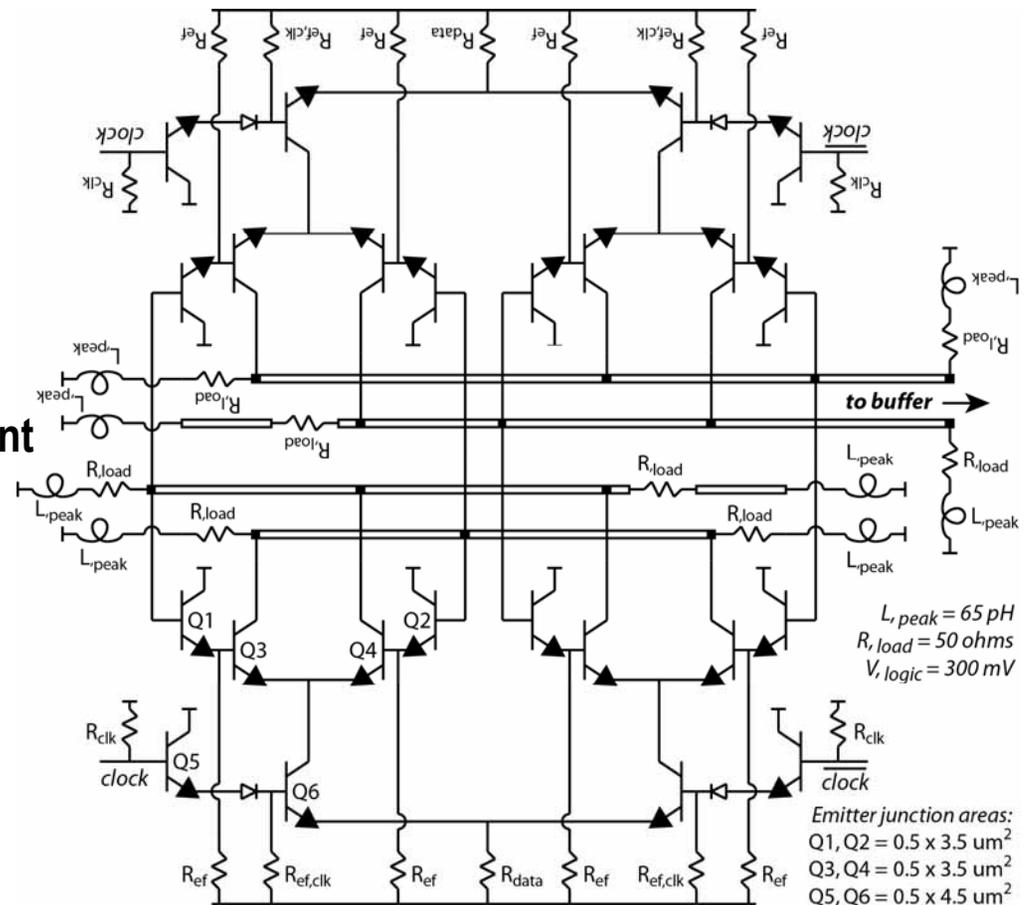
ECL Master-Slave Latch with Inverting Feedback

Forms 2:1 Frequency Divider.

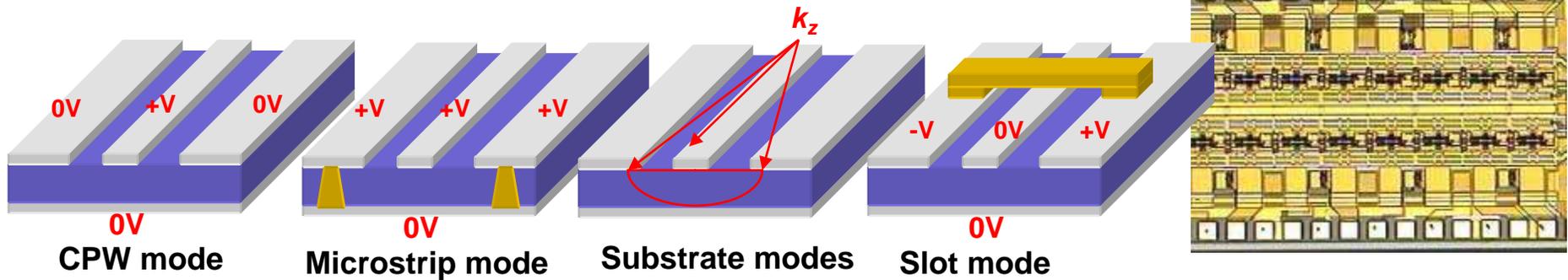
Maximum clock frequency is measure of technology speed.

Standard circuit configuration for consistent benchmarking - **no tricks.**

Small inductive peaking ($L/R \sim 1.3$ ps).

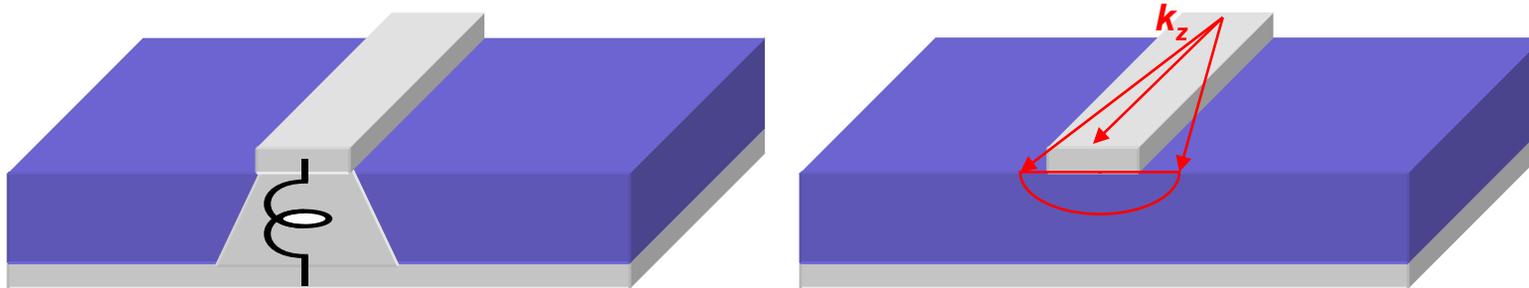


CPW has parasitic modes, coupling from poor ground plane integrity

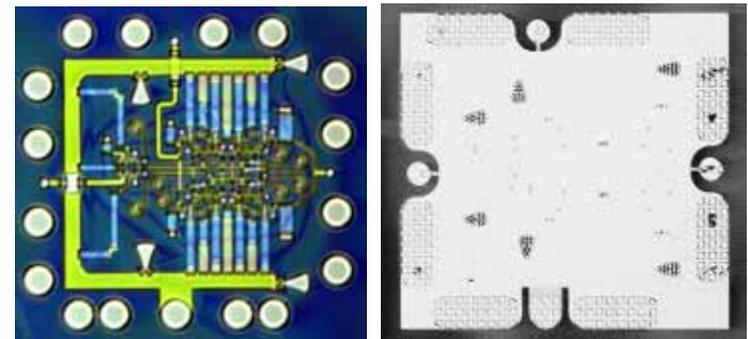
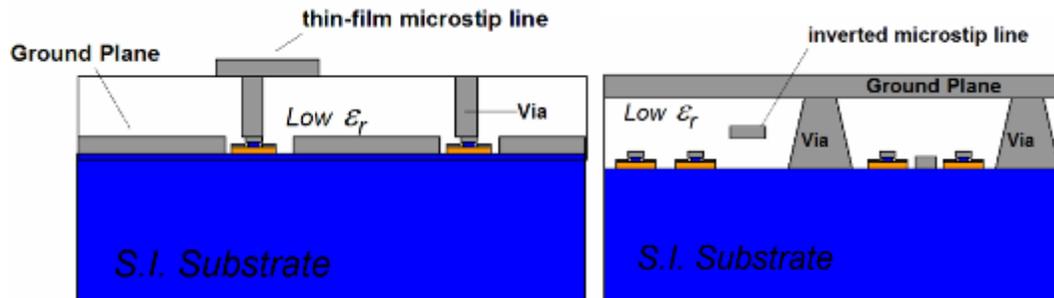


*ground straps suppress slot mode, but multiple ground breaks in complex ICs produce ground return inductance
ground vias suppress microstrip mode, wafer thinning suppresses substrate modes*

Microstrip has high via inductance, has mode coupling unless substrate is thin.

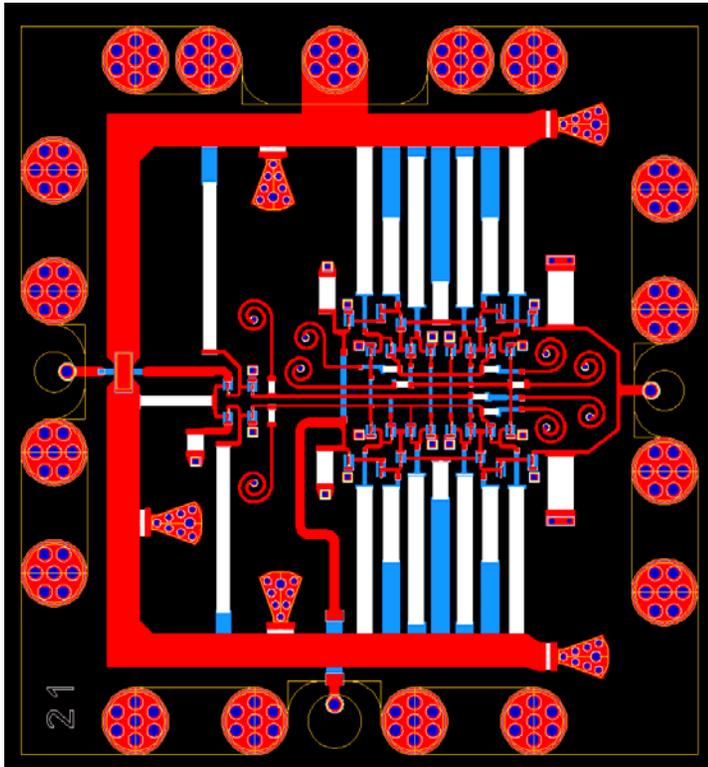


We prefer (credit to NTT) thin-film microstrip wiring, inverted is best for complex ICs

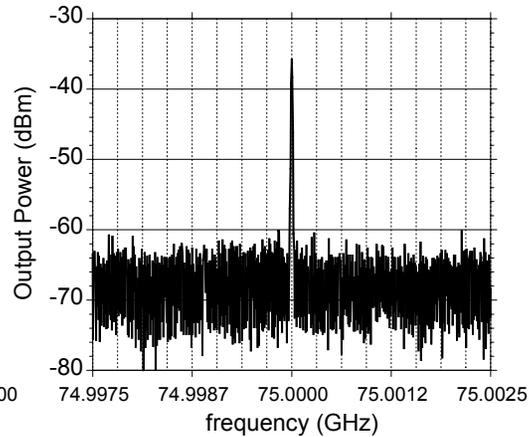
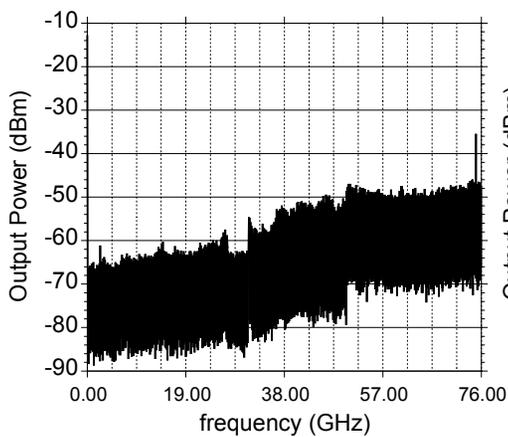
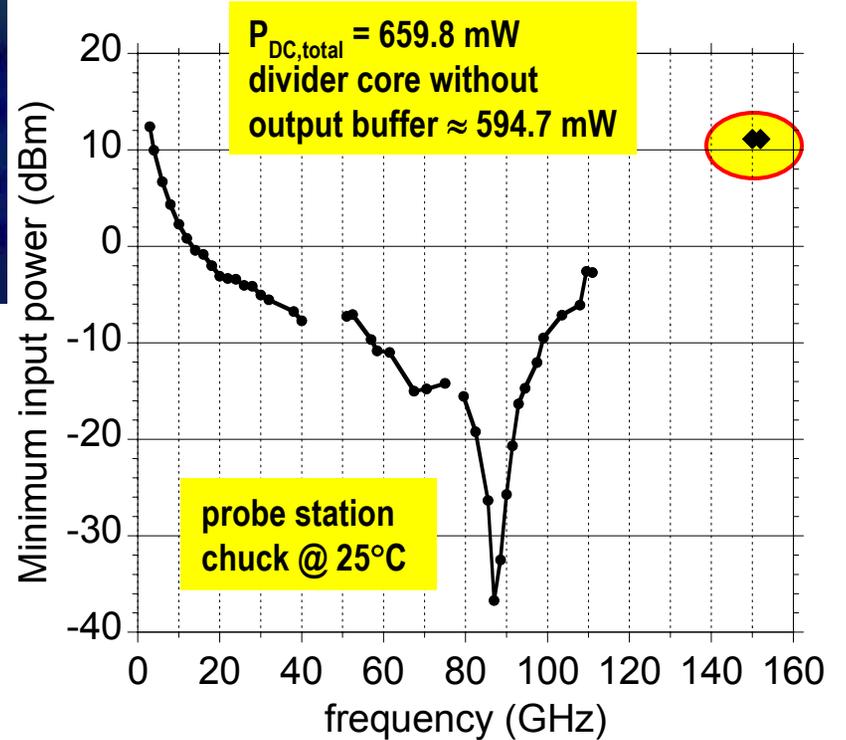
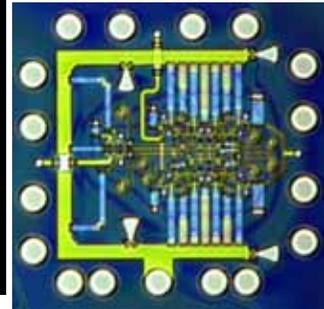


IC design: Z. Griffith, UCSB
 HBT design: RSC / UCSB / GCS
 IC Process / Fabrication: GCS
 Test: UCSB / RSC / Mayo

UCSB / RSC / GCS 150 GHz Static Frequency Dividers



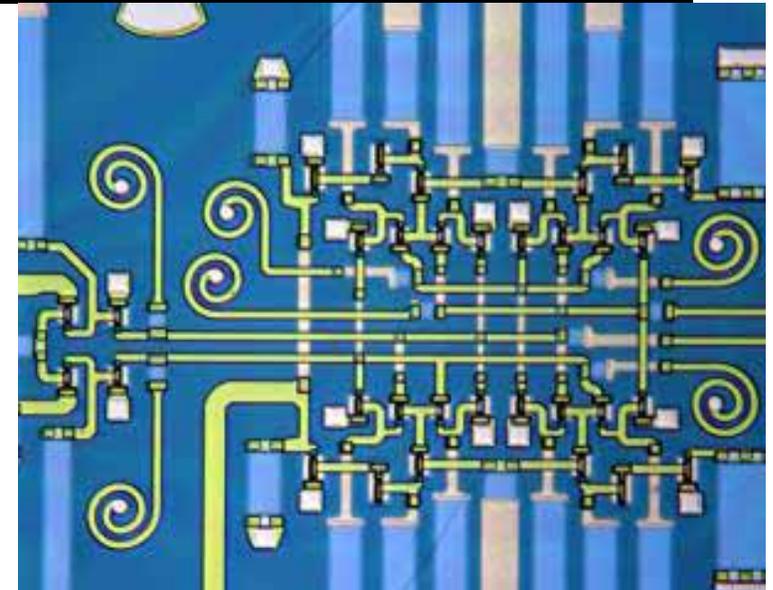
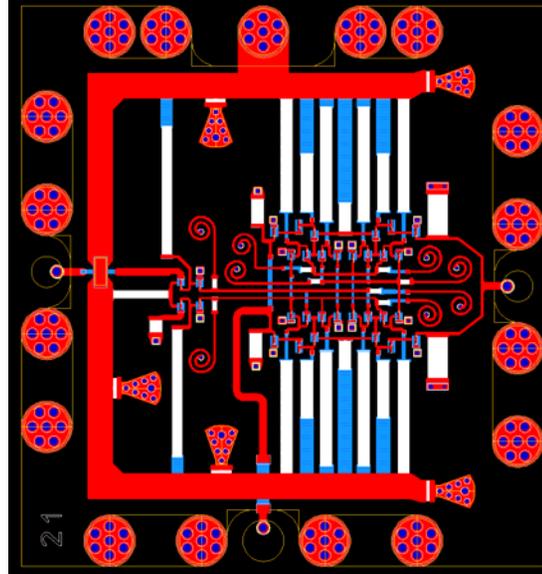
	units	data current steering	data emitter followers	clock current steering	clock emitter followers
size	μm^2	0.5 x 3.5	0.5 x 4.5	0.5 x 4.5	0.5 x 5.5
current density	$\text{mA}/\mu\text{m}^2$	6.9	4.4	4.4	4.4
C_{cb}/I_c	psec / V	0.59	0.99	0.74	0.86
V_{cb}	V	0.6	0	0.6	1.7
f_τ	GHz	301	260	301	280
f_{max}	GHz	358	268	358	280



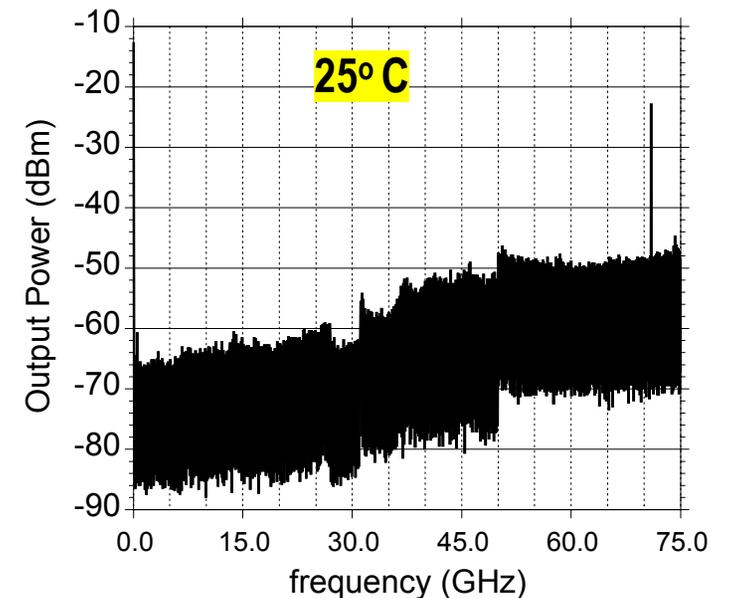
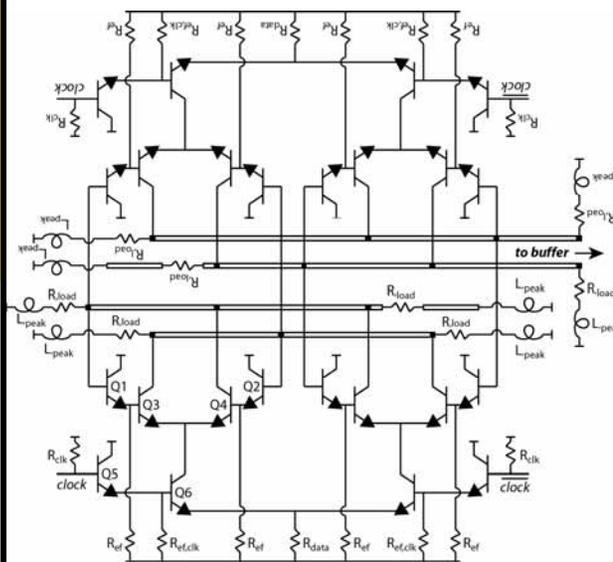
UCSB 142 GHz Master-Slave Latches (Static Frequency Dividers)

Static 2:1 divider:
 Standard digital benchmark.
 Master-slave latch
 with inverting feedback.
 Performance comparison
 between digital technologies

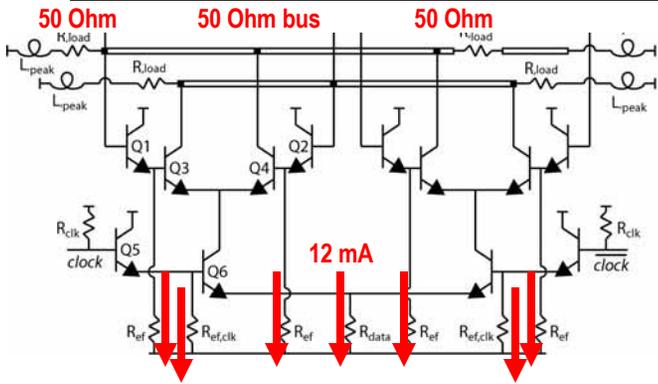
UCSB technology 2004:
 InP mesa HBT technology
 12-mask process
 600 nm emitter width
 142 GHz maximum clock.



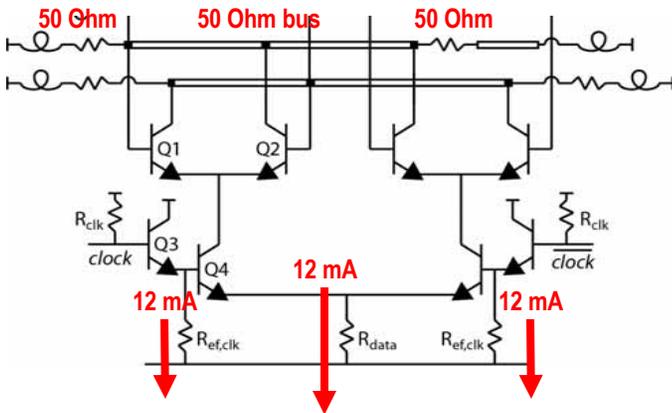
Implications:
 160 Gb/s fiber ICs
 100 + Gb/s serial links
 Target is 260 GHz clock rate
 at 300 nm scaling generation



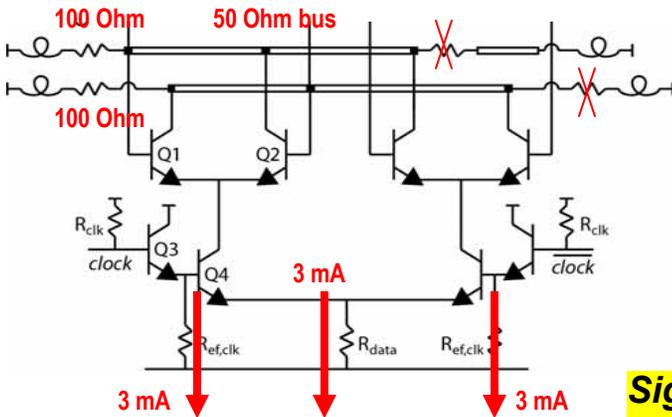
Reducing Digital Circuit Dissipation



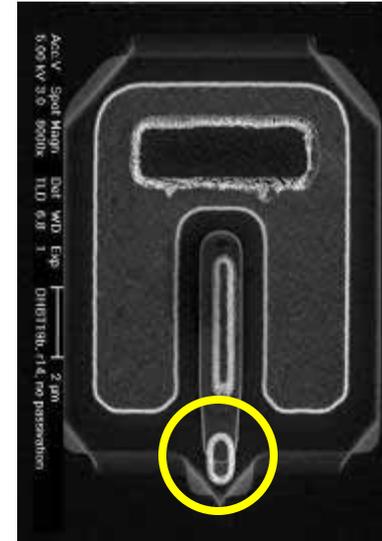
ECL with impedance-matched 50 Ohm bus:
 25 Ohm load \rightarrow switch 12 mA
 $12 \text{ mA} \times 7 \times 4 \text{ V} = 336 \text{ mW/latch}$



CML with impedance-matched 50 Ohm bus:
 25 Ohm load \rightarrow switch 12 mA
 $12 \text{ mA} \times 3 \times 3 \text{ V} = 108 \text{ mW/latch}$



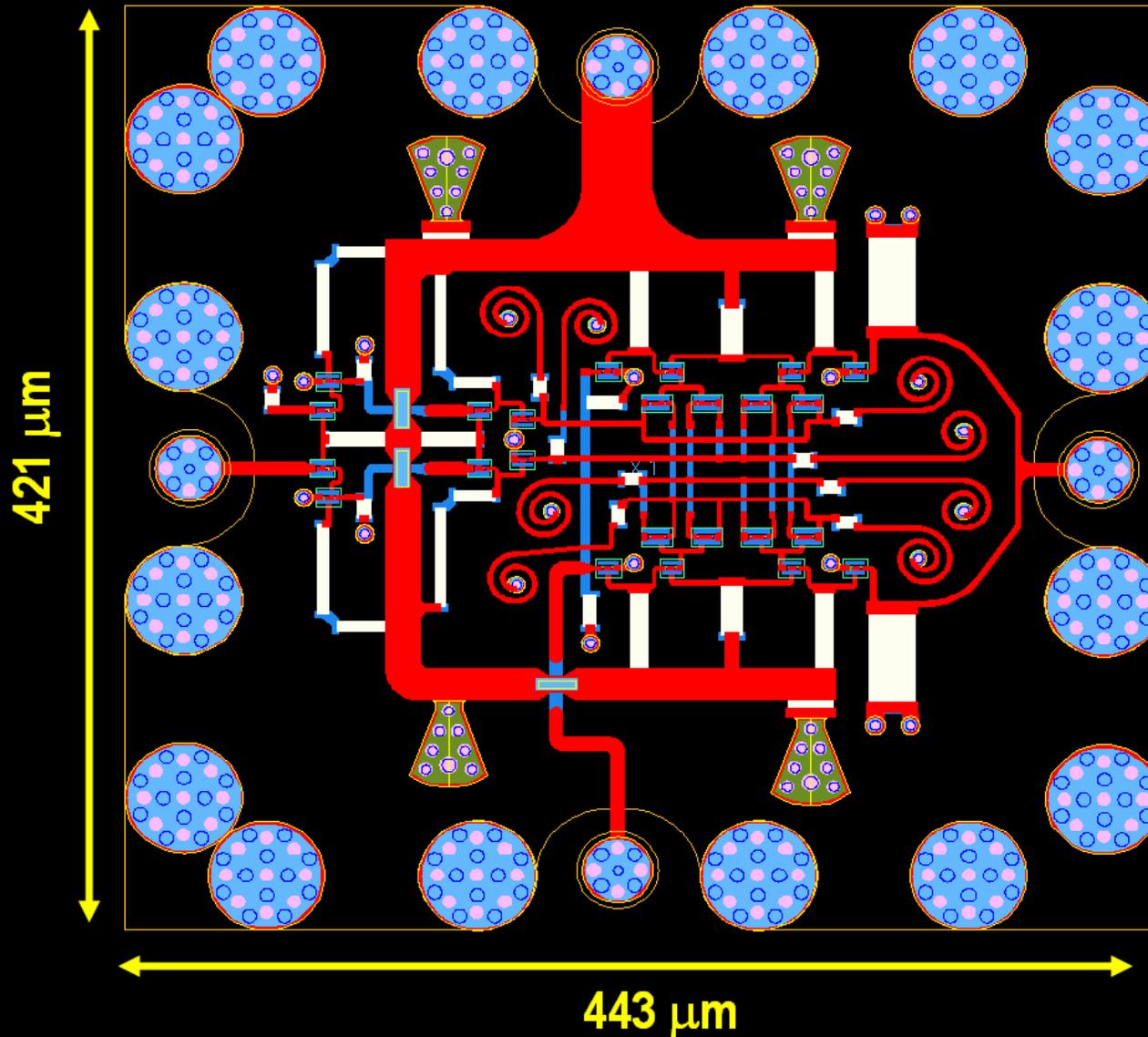
Low-Power CML
 100 Ohm loaded \rightarrow switch 3 mA
 $3 \text{ mA} \times 3 \times 3 \text{ V} = 27 \text{ mW/latch}$



High speed @ low power = low C_{wiring} , low $C_{cb,pad}$

Significant dissipation in the clock emitter-follower level-shifters; some published work omits this from stated dissipation

Low Power CML Static Divider Designs



Simulated divider speed...

Without C_{cb} reduction

$$A_{jbe} = 3.0 \mu\text{m}^2, \quad f_{\text{max}} = 130 \text{ GHz}$$

$$A_{jbe} = 2.5 \mu\text{m}^2, \quad f_{\text{max}} = 136 \text{ GHz}$$

With Implanted Sub-collector

$$A_{jbe} = 3.0 \mu\text{m}^2, \quad f_{\text{max}} = 143 \text{ GHz}$$

$$A_{jbe} = 2.5 \mu\text{m}^2, \quad f_{\text{max}} = 151 \text{ GHz}$$

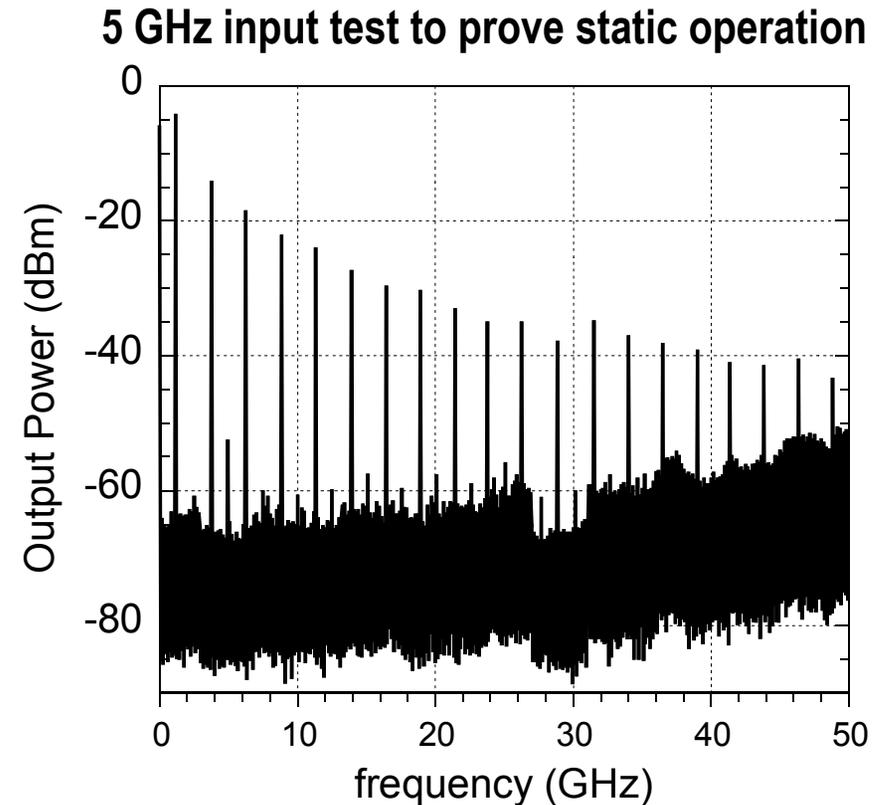
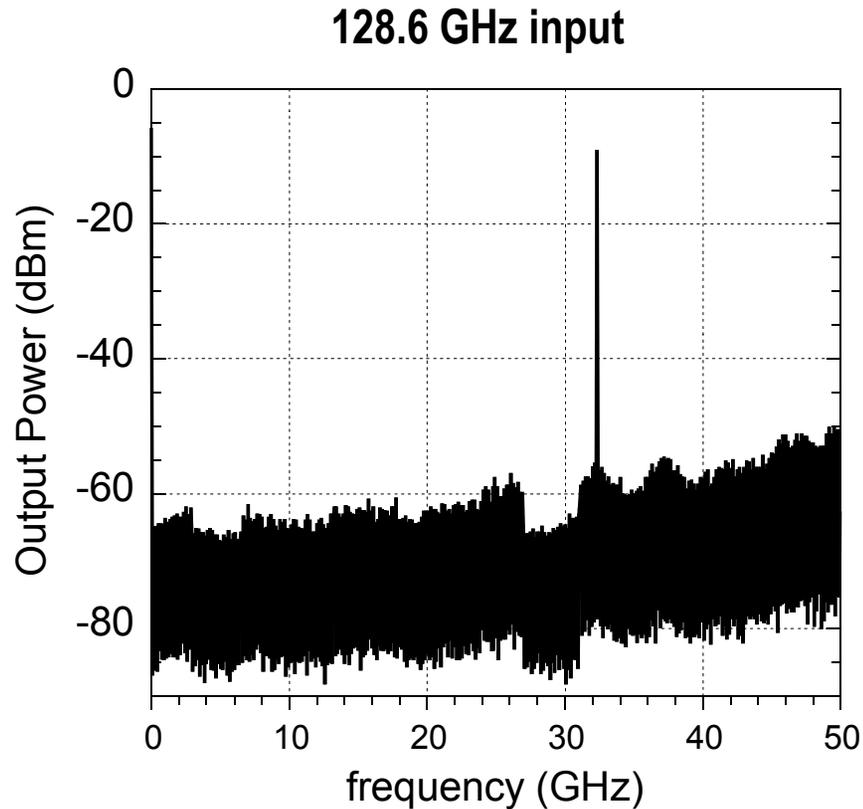
With Pedestal

$$A_{jbe} = 3.0 \mu\text{m}^2, \quad f_{\text{max}} = 156 \text{ GHz}$$

$$A_{jbe} = 2.5 \mu\text{m}^2, \quad f_{\text{max}} = 164 \text{ GHz}$$

$$P_{\text{divider core}} \approx 214 \text{ mW}$$

Divide-by-4 at 128.6 GHz, S³ RSC Technology



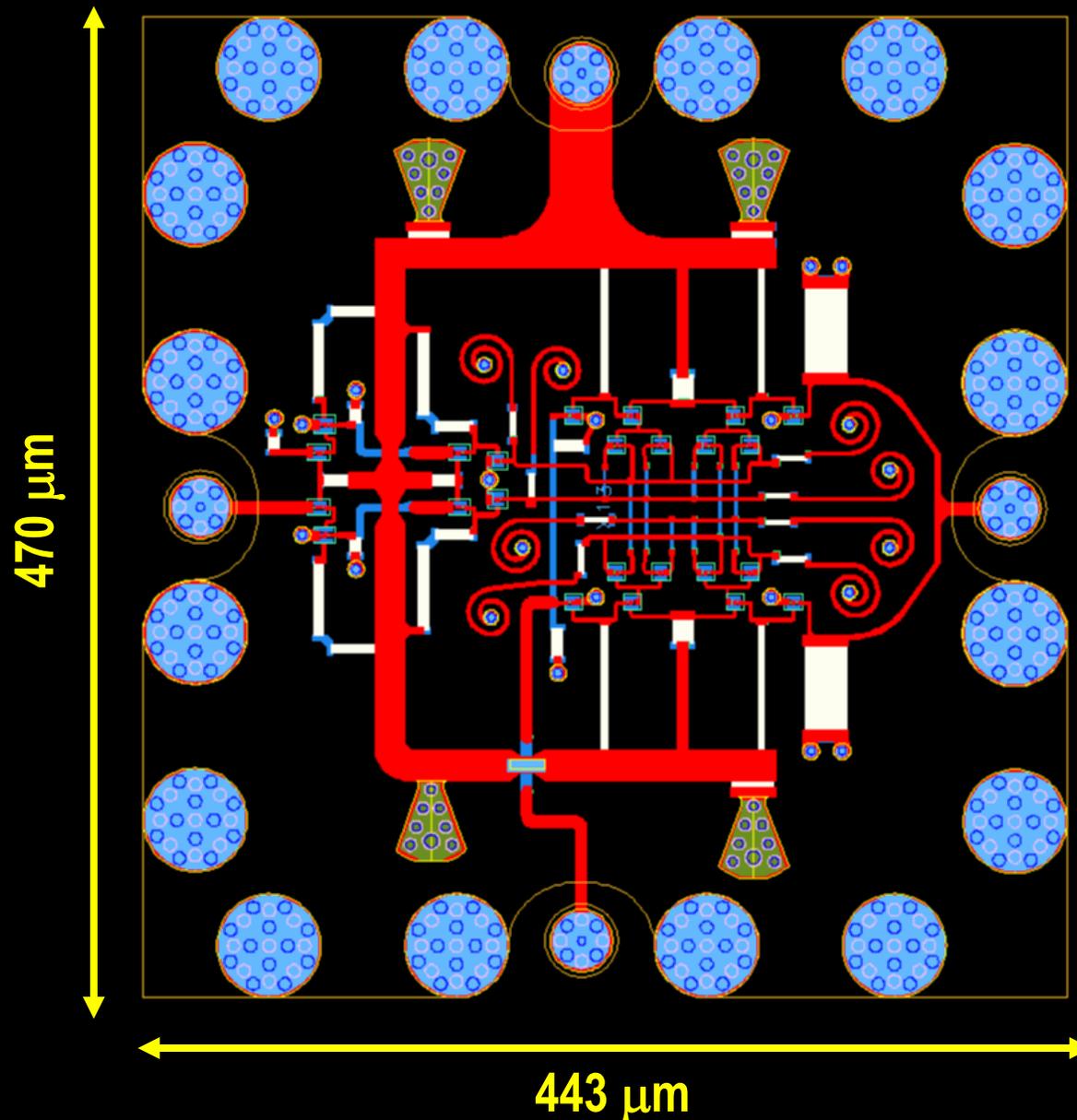
Measurements performed at UCSB, GUNN Source Used For CLK Input

RSC Wafer # xxxx, Divider ID: R3C2 #5A, Fabricated at RSC, Design at UCSB

$V_{\text{clk offset}} = -0.45 \text{ V}$, $V_{\text{EE, div1,2}} = -3.4 \text{ V}$, $I_{\text{EE, total}} = 192 \text{ mA} - I_{\text{div1,2}}$ at $f_{\text{clk,max}} \leq 65 \text{ mA}$ per divider ckt

Power dissipation of input divider core w/out output buffer < 221 mW — room temp, no cooling

Ultra Low Power CML Static Divider Design



Simulated divider speed...

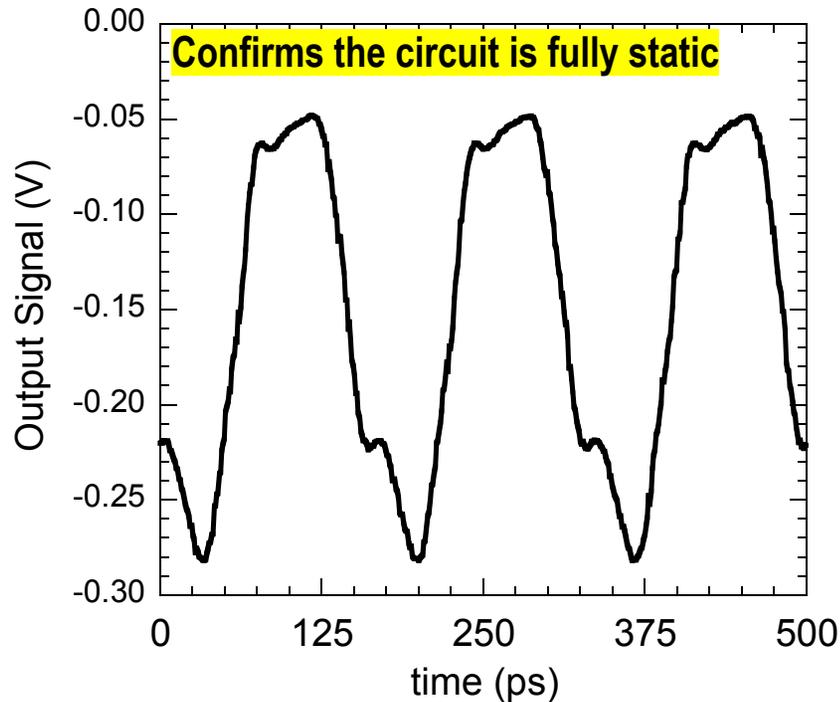
With Collector Pedestal

$$A_{jbe} = 1.0 \mu\text{m}^2, \quad f_{\text{max}} = 100 \text{ GHz}$$

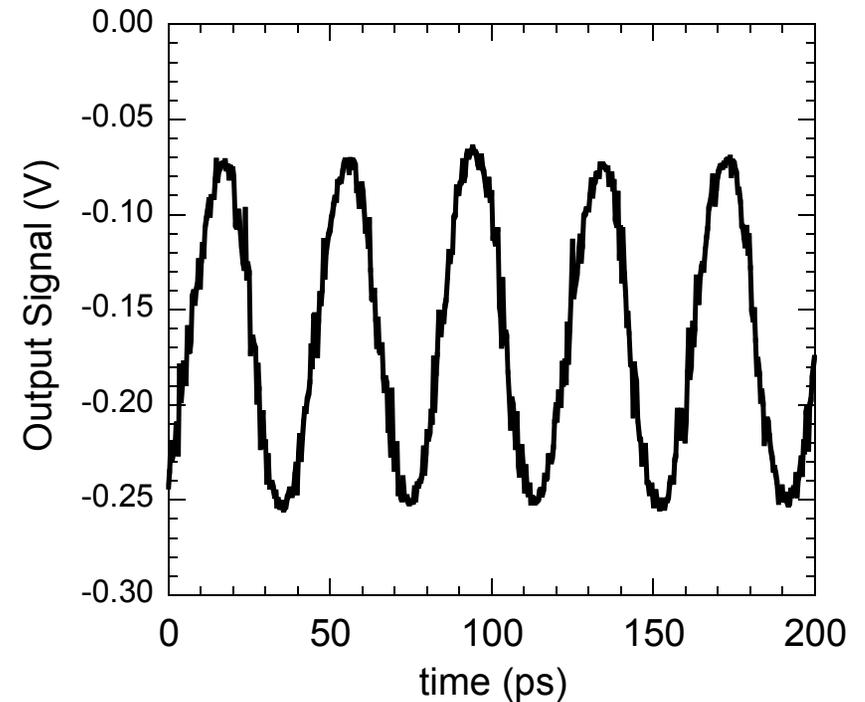
$$P_{\text{divider core}} \approx 31 \text{ mW}$$

Ultra low-power RSC / UCSB CML dividers

Output waveform @ 6.0 GHz, $f_{clk} = 12$ GHz



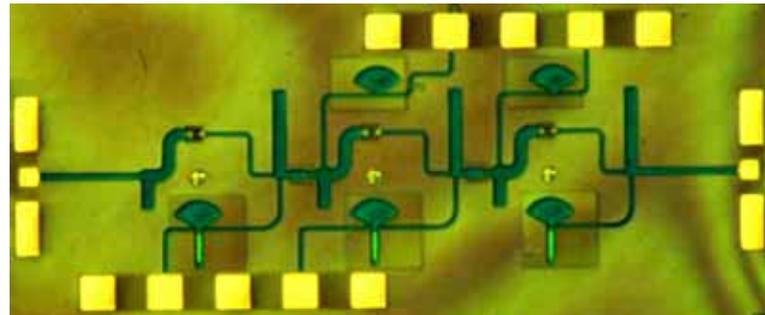
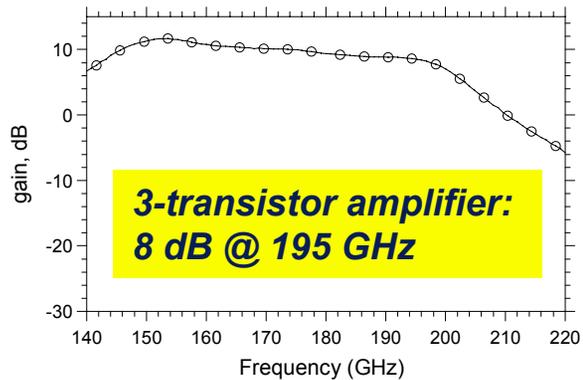
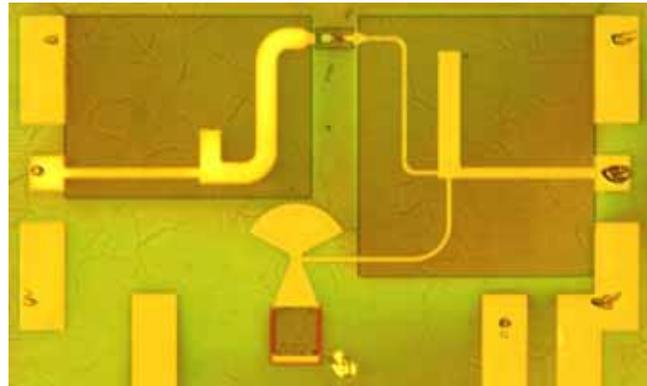
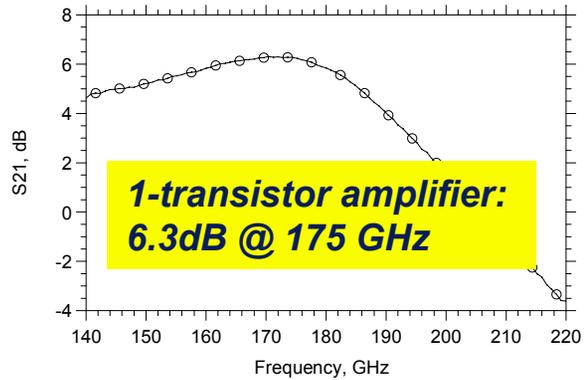
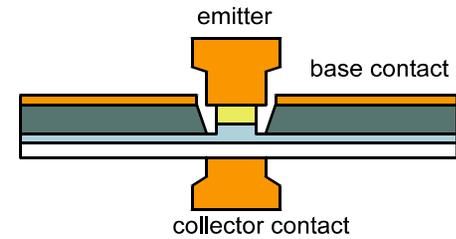
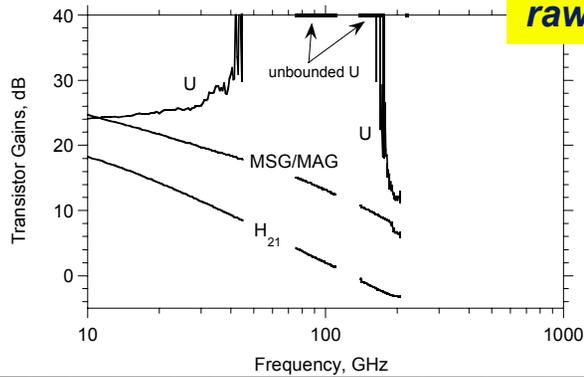
Output waveform @ 25.5 GHz, $f_{clk} = 51$ GHz



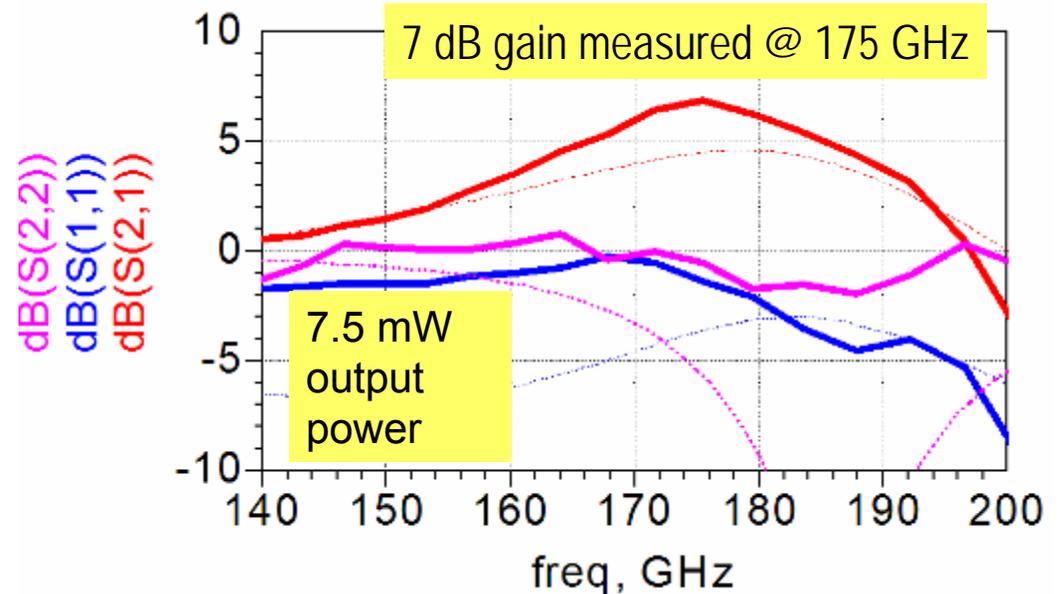
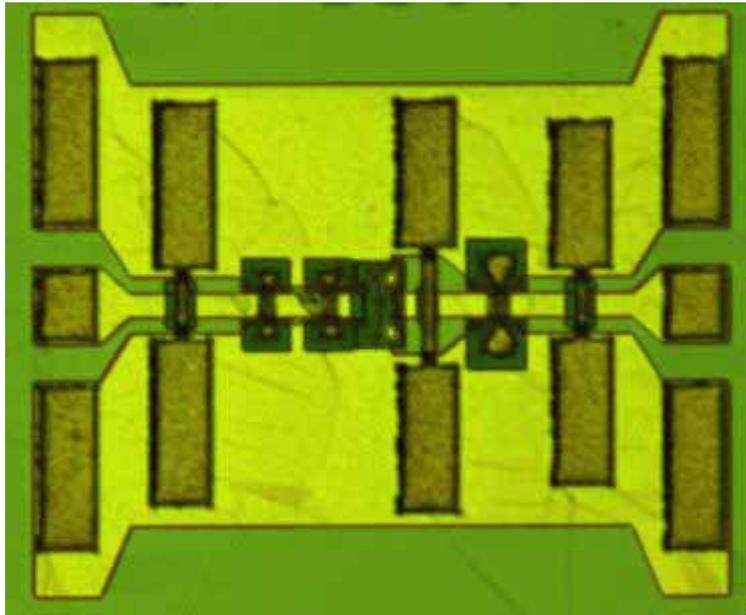
The divider is operational from 12 GHz to 51 GHz

At $f_{clk} = 51$ GHz, $P_{flip-flop} = 29.2$ mW \rightarrow Latch power \times delay = 143 fJ, no emitter followers = 79.0 fJ

Deep Submicron Bipolar Transistors for 140-220 GHz Amplification



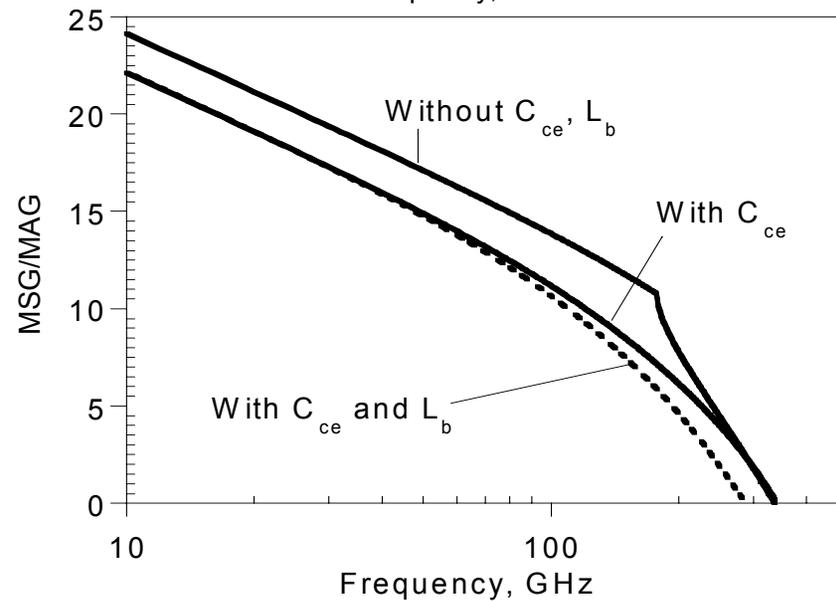
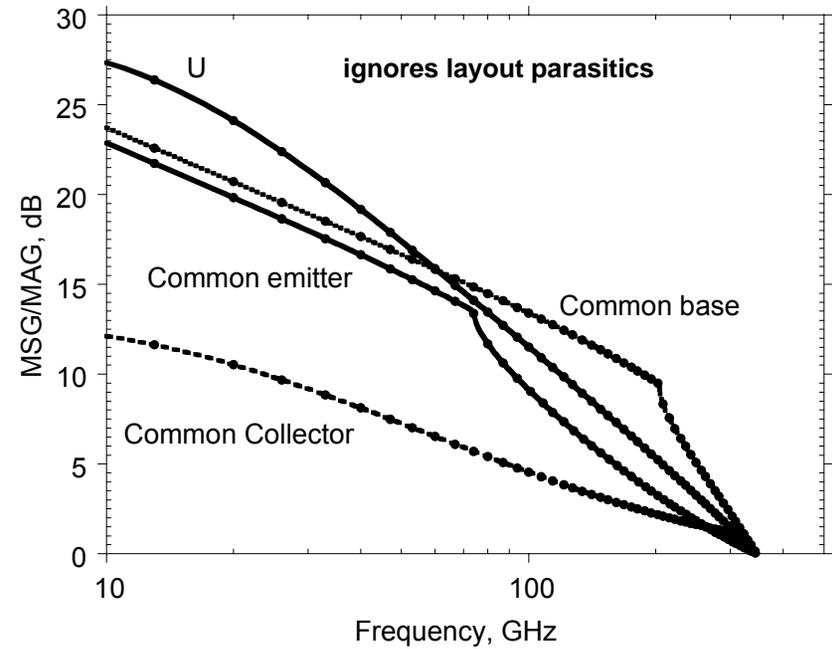
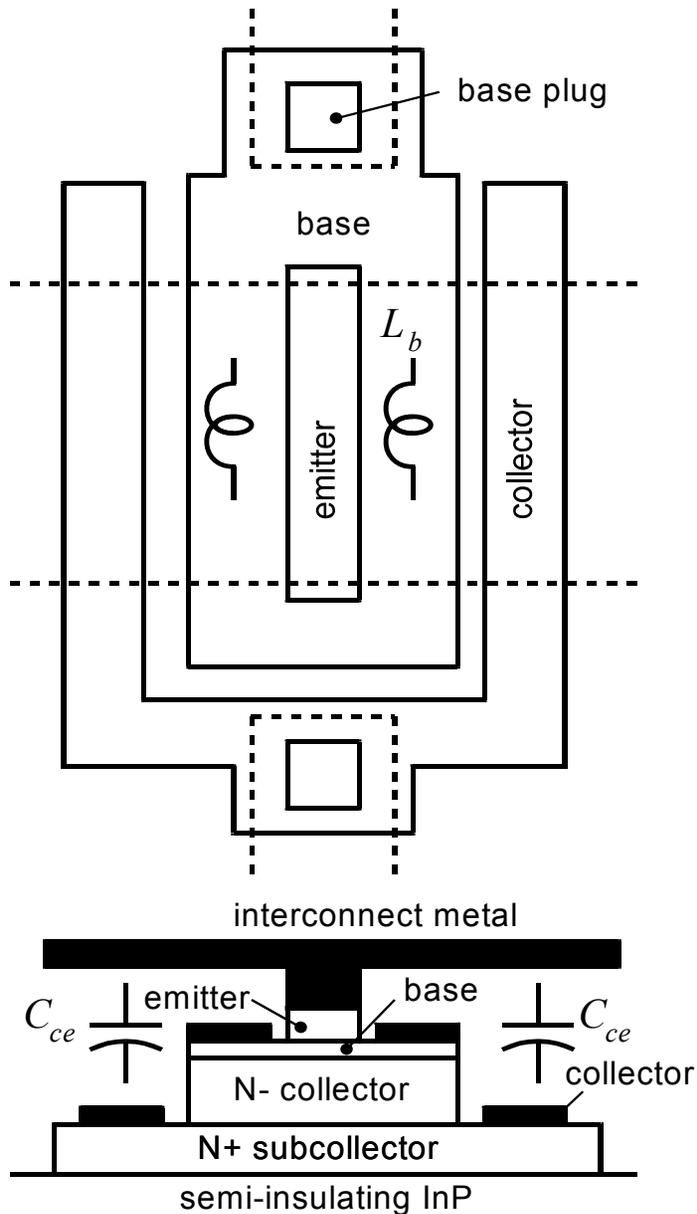
Mesa DHBT Power Amplifiers for 100-200 GHz Communications



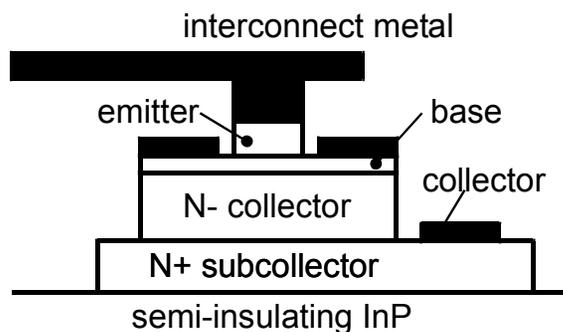
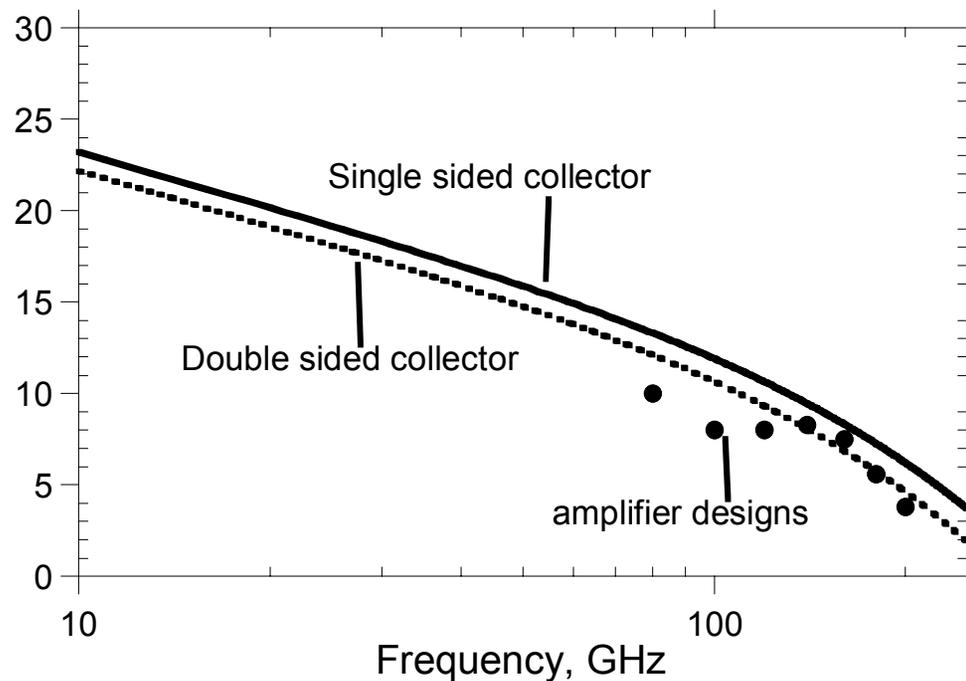
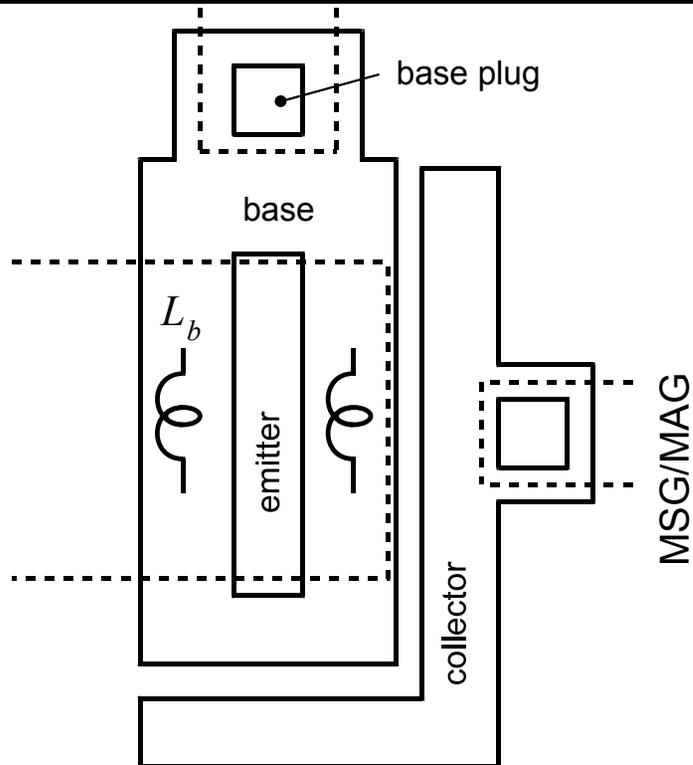
175 GHz Power Amplifier Demonstrated in a 300 GHz f_{max} process
500 GHz f_{max} DHBTs available now, 600 GHz should be feasible soon
 → **feasibility of power amplifiers to 350 GHz**
 → **Ultra high frequency communications**

2 fingers x 0.8 μm x 12 μm , ~ 250 GHz f_{τ} , 300 GHz f_{max} , $V_{br} \sim 7\text{V}$, ~ 3 mA/ μm^2 current density

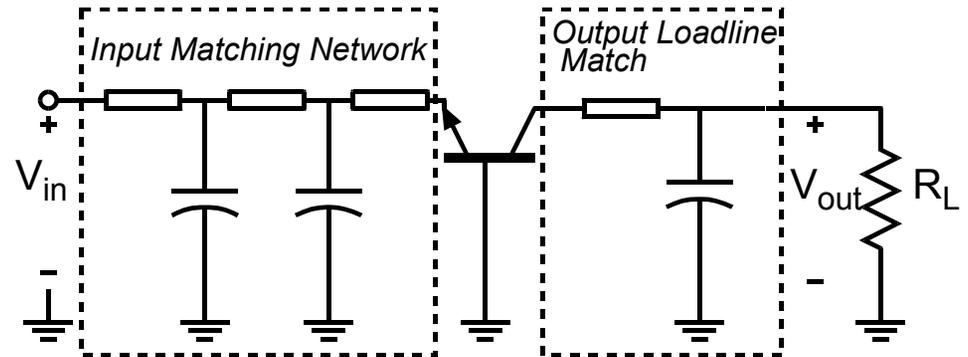
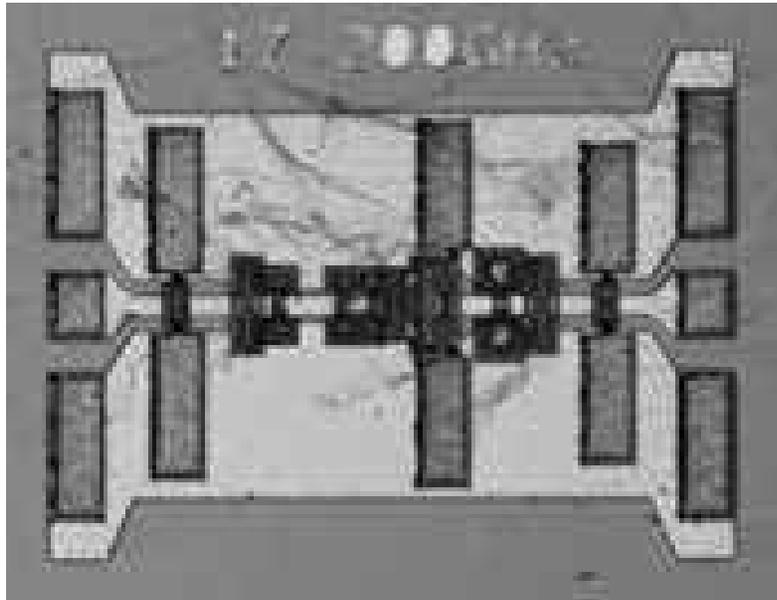
Common-Base Has Highest Gain, but Layout Parasitics Matter !



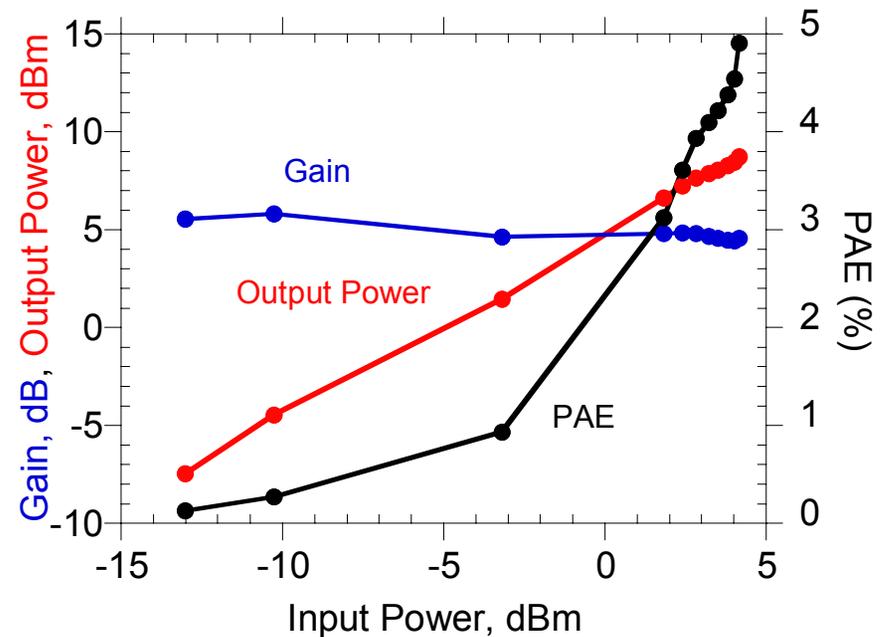
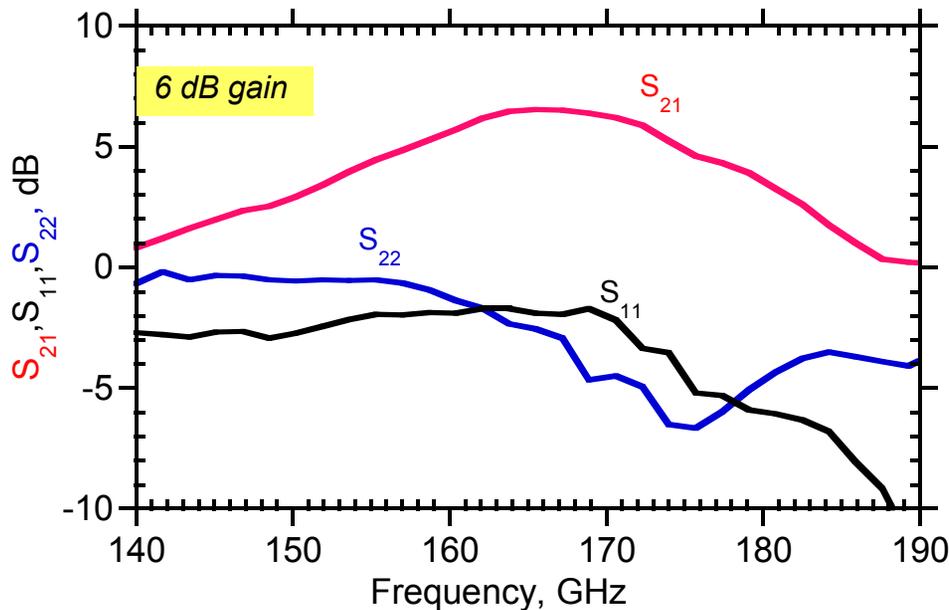
Single-Sided Collector Contacts Improve Common-Base Gain



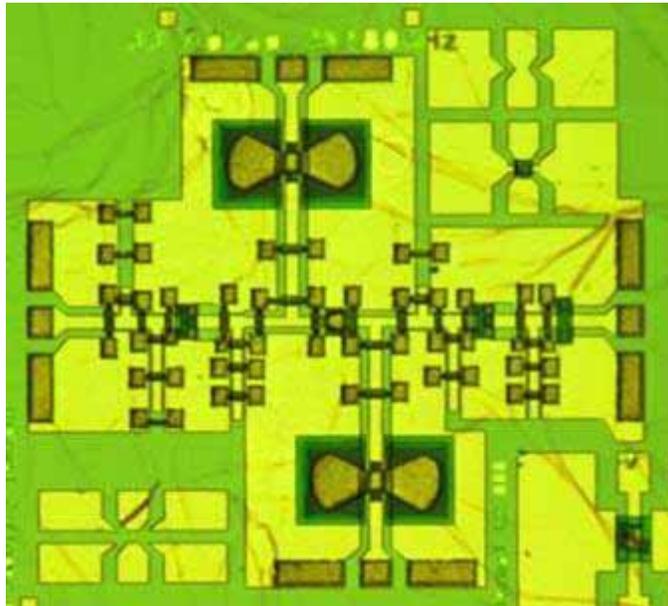
172 GHz Common-Base Power Amplifier



8.3 dBm saturated output power
4.5-dB associated power gain at 172 GHz
 DC bias: $I_c=47\text{ mA}$, $V_{cb}=2.1\text{ V}$.



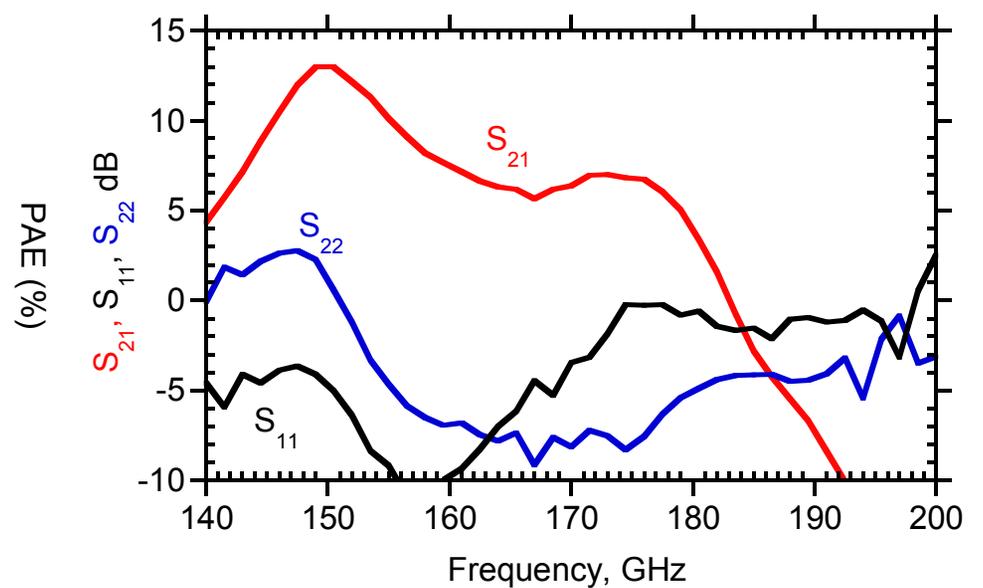
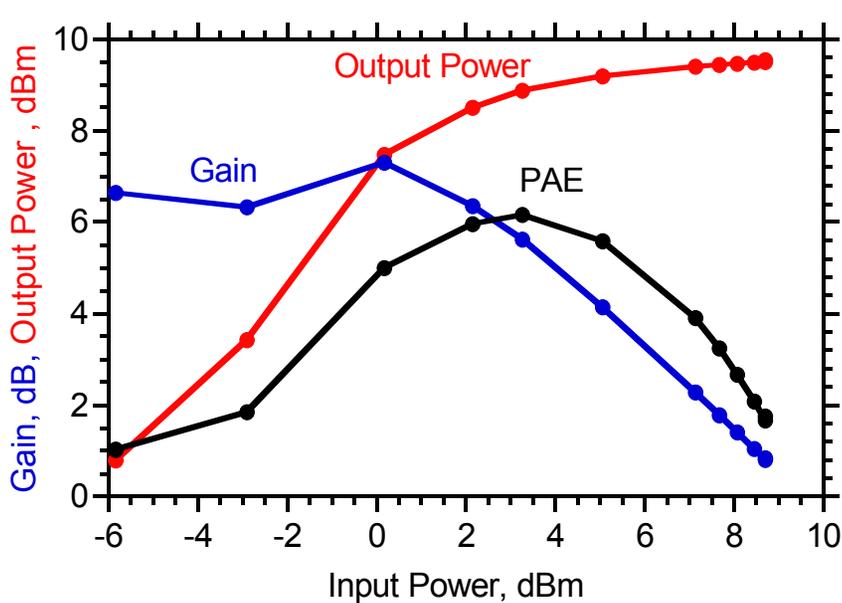
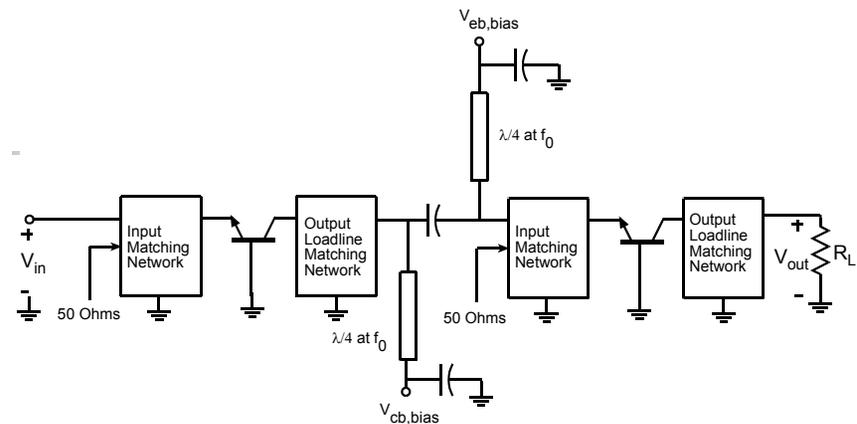
176 GHz Two-Stage Amplifier



7-dB gain at 176 GHz

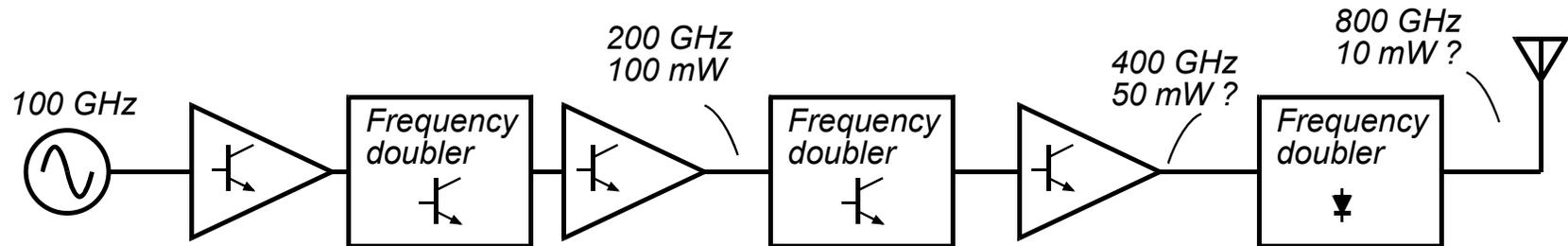
8.1 dBm output power, 6.3 dB power gain at 176 GHz

9.1 dBm saturated output power at 176 GHz

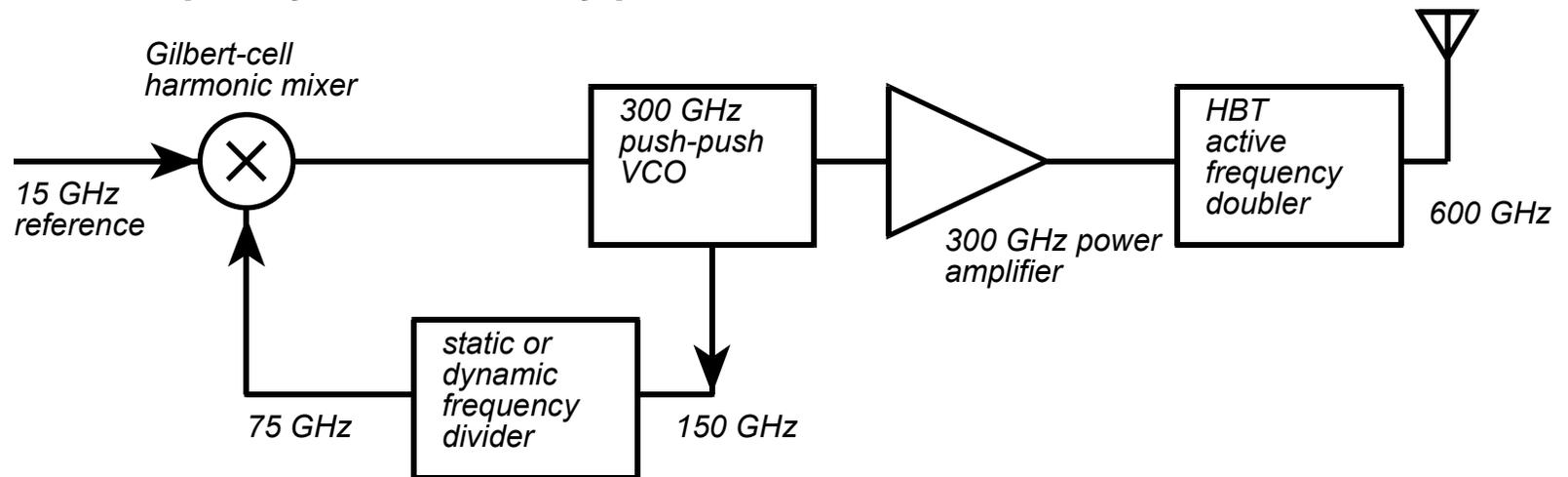


Transistor ICs → compact sub-mm-wave systems

Compact, Single-Chip Monolithic Frequency Multiplier Chains



Sub-mm-wave Frequency Generation by phase-locked source

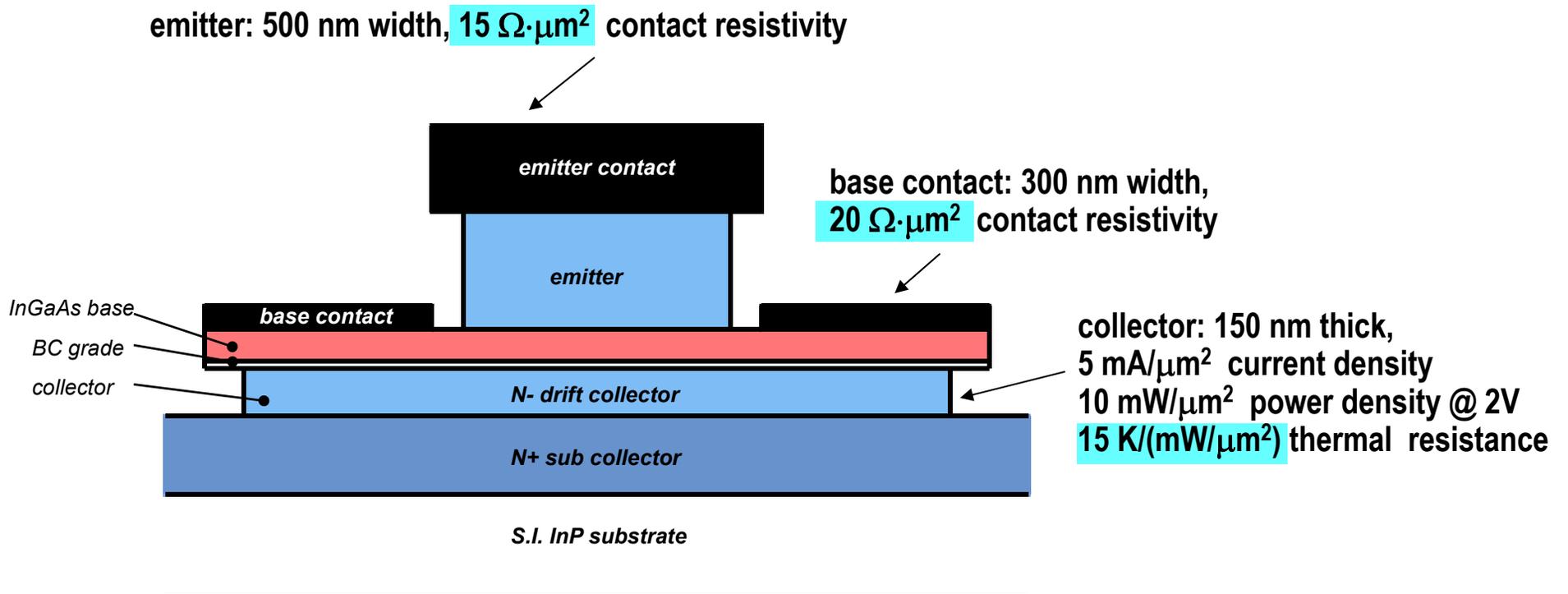


Today: InP DHBTs @ 500 nm Scaling Generation

Device Performance: ~ 400 GHz f_{τ} and ~500 GHz f_{\max}

Has enabled 150 GHz digital clock rate (static dividers)

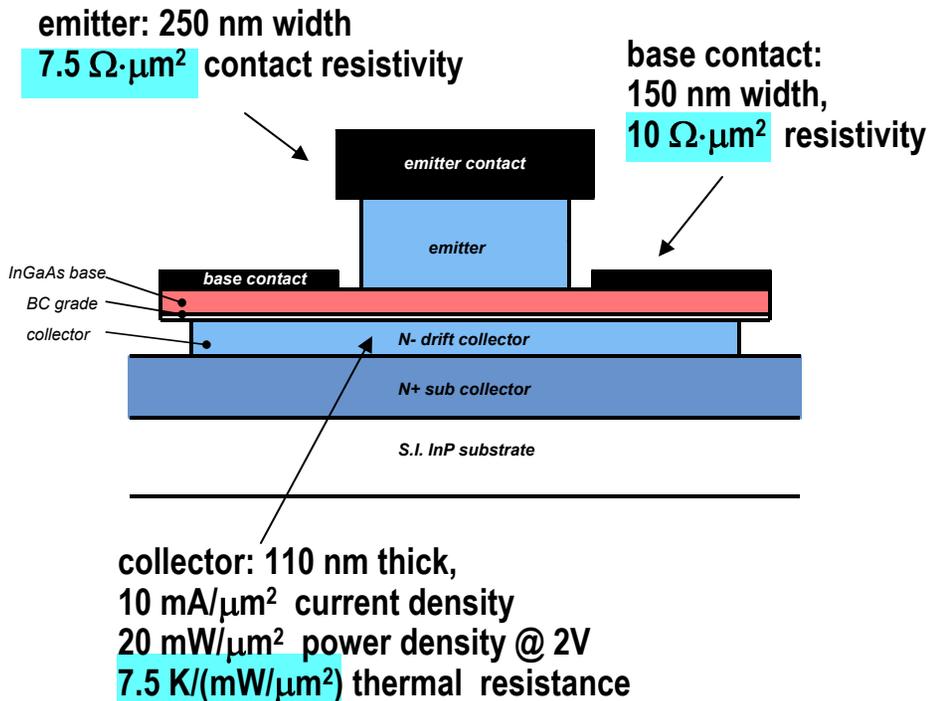
Should enable 300 GHz power amplifiers (175 GHz realized with 300 GHz f_{\max})



Next: 250 nm Scaling Generation, 1.414:1 faster

Goals: 500 GHz f_{τ} and 700 GHz f_{\max}
 230 GHz digital clock rate (static dividers)
 400 GHz power amplifiers

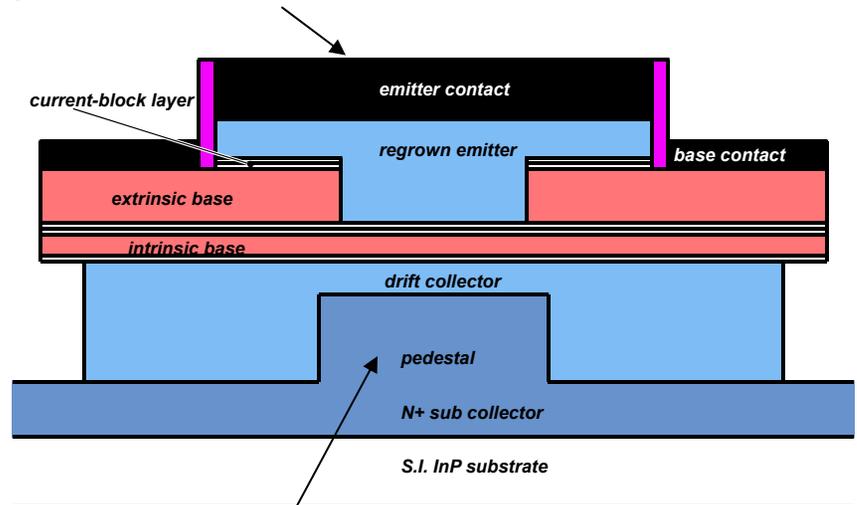
Direct, brute-force scaling



Requires innovations in emitter & base contacts: processes & metallurgy

Parasitic Reduction

regrown emitter with wide contact: reduces access resistance

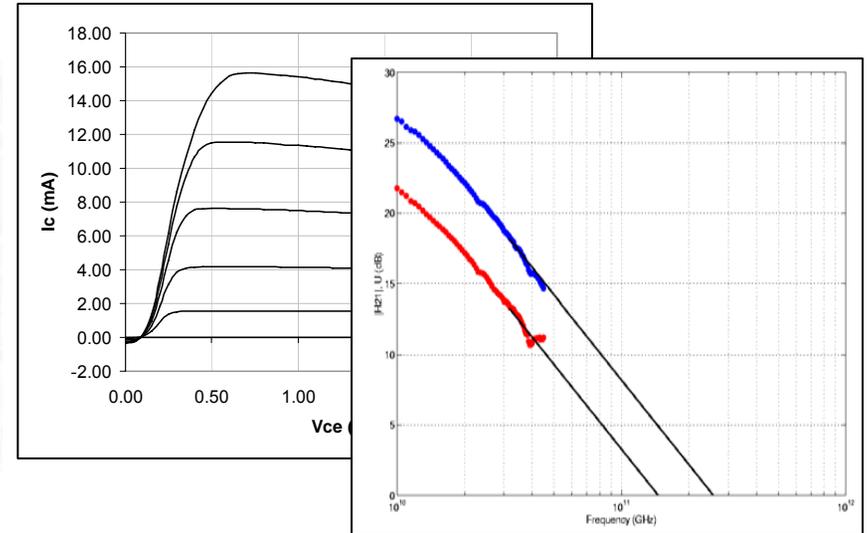
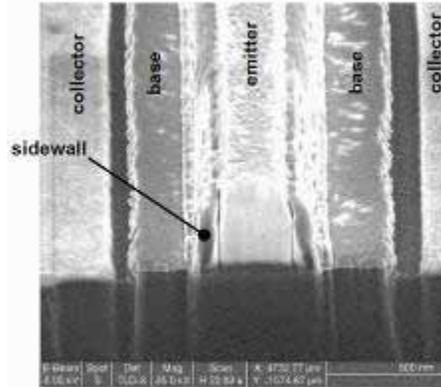
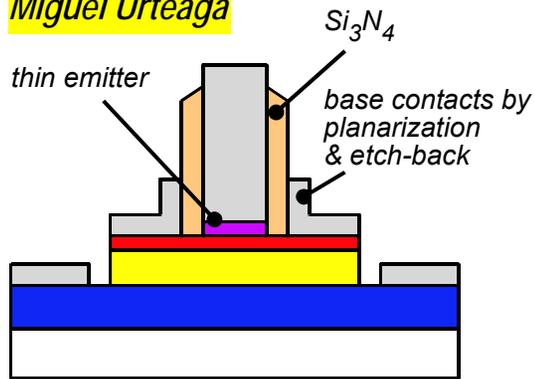


collector pedestal:
 reduces capacitance under base contacts,
 allows wider & more resistive base contacts

Requires implants and regrowth processes

Manufacturable Emitter Dielectric Sidewall Processes

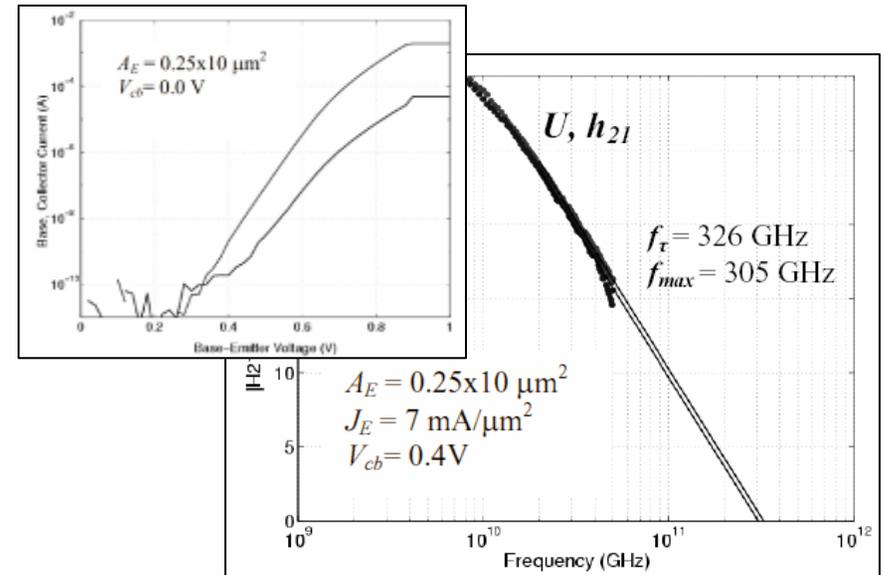
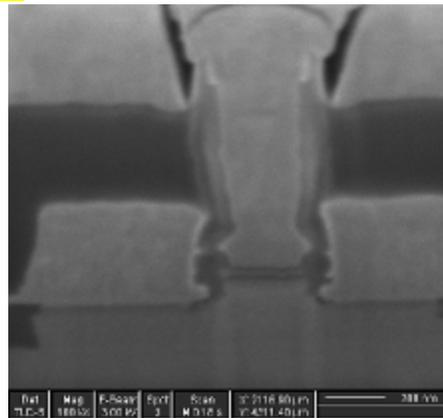
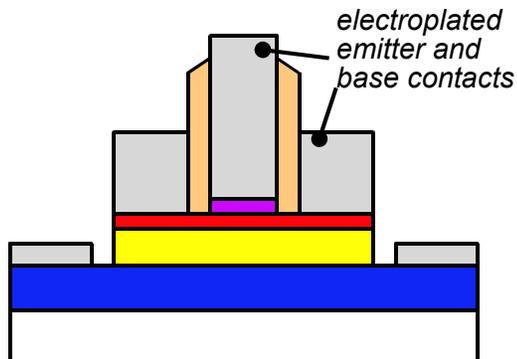
First-Generation: UCSB and Rockwell Scientific Miguel Urteaga



Urteaga, Rodwell, Pierson, Rowell, Brar, Nguyen, Nguyen: UCSB, RSC, GCS

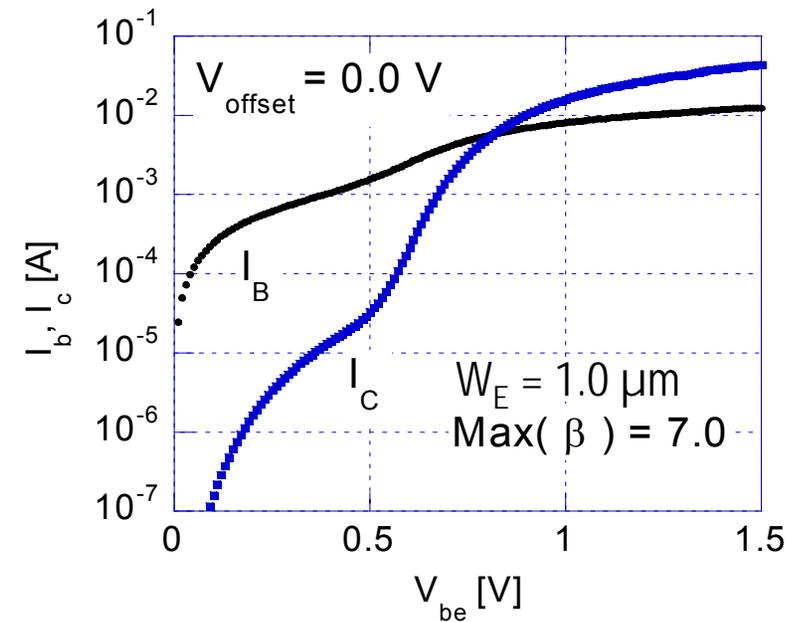
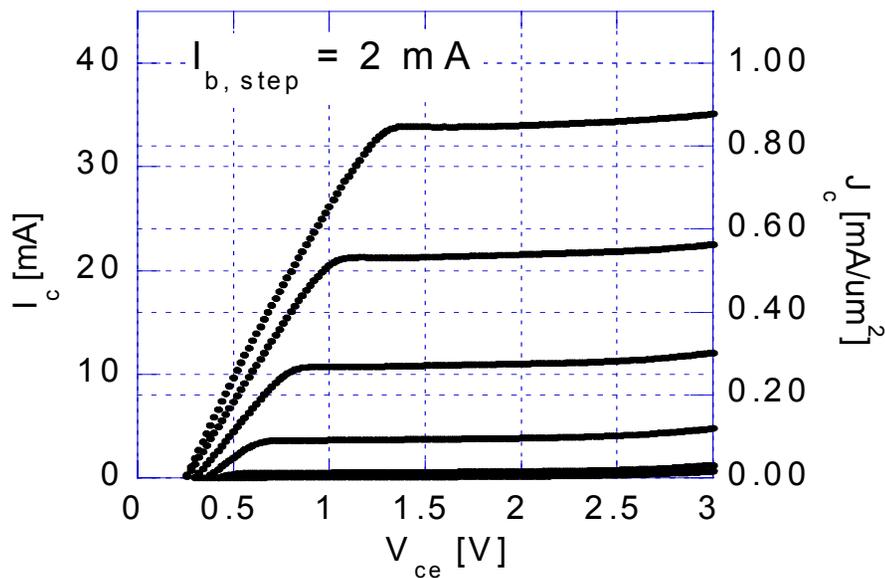
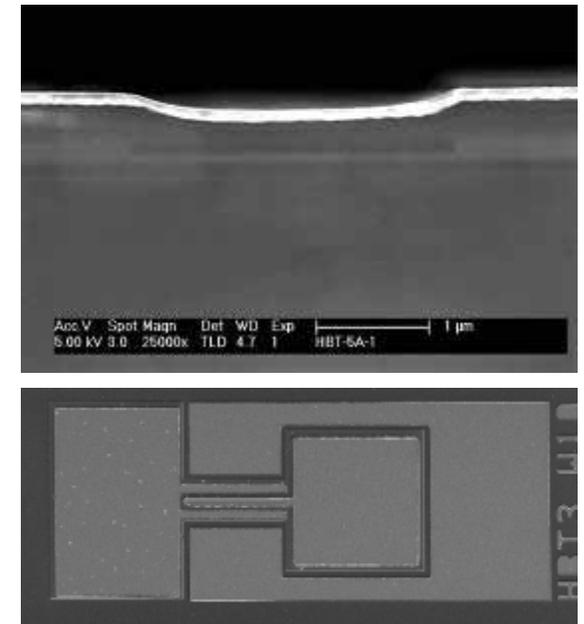
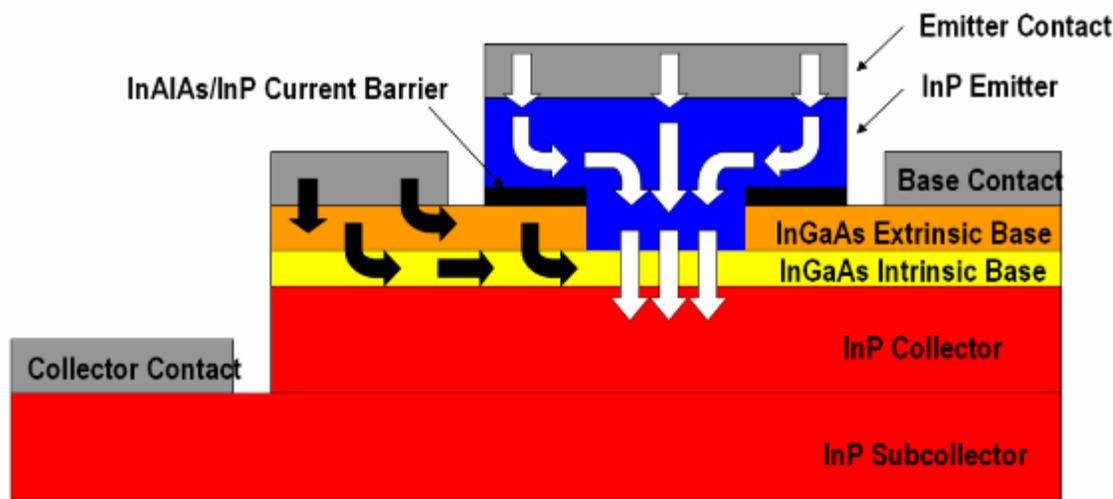
266 GHz f_t , 133 GHz f_{max} , $C_{cb}/I_c = 0.4$ ps/V

2nd-Generation: Rockwell Scientific Miguel Urteaga, Petra Rowell

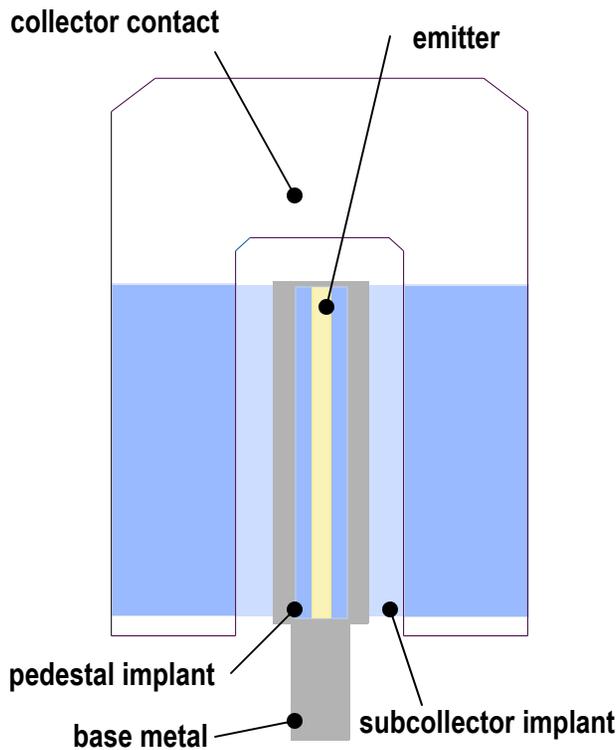
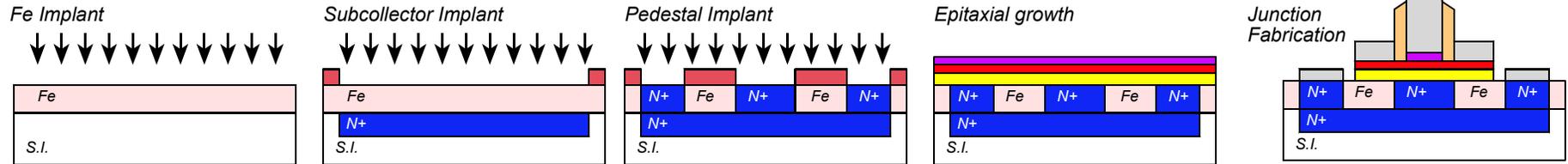


Urteaga, Rowell, Pierson, Brar: RSC

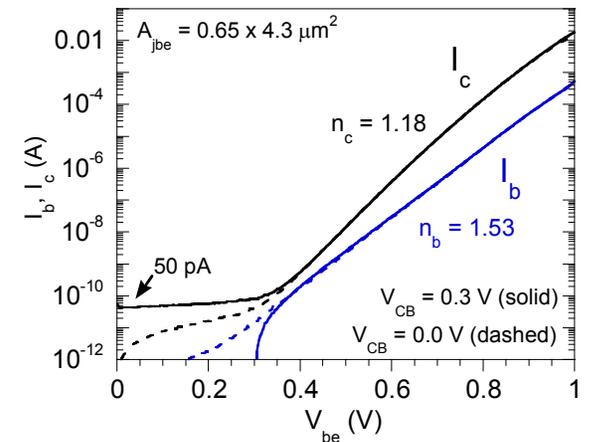
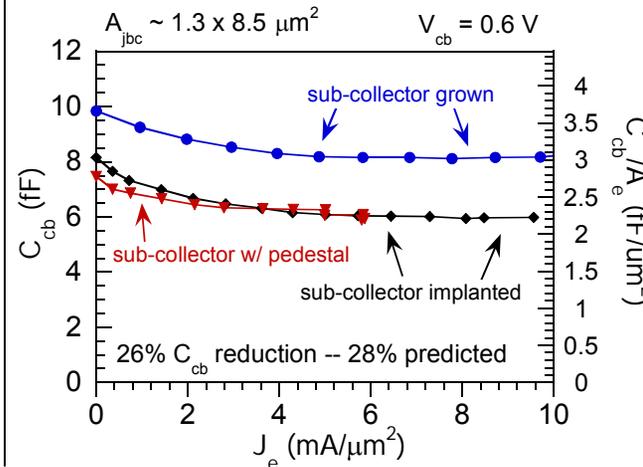
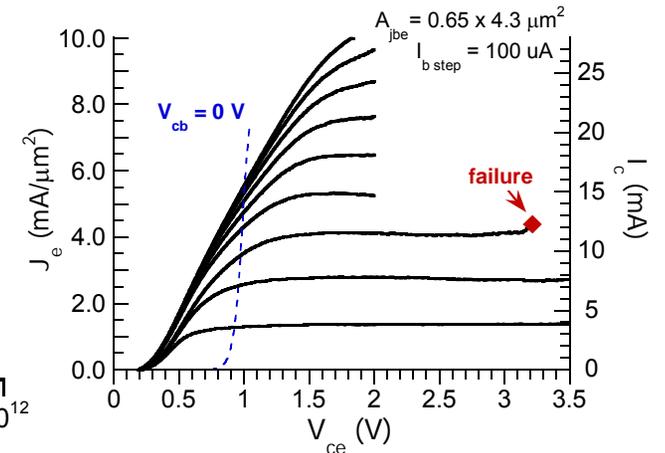
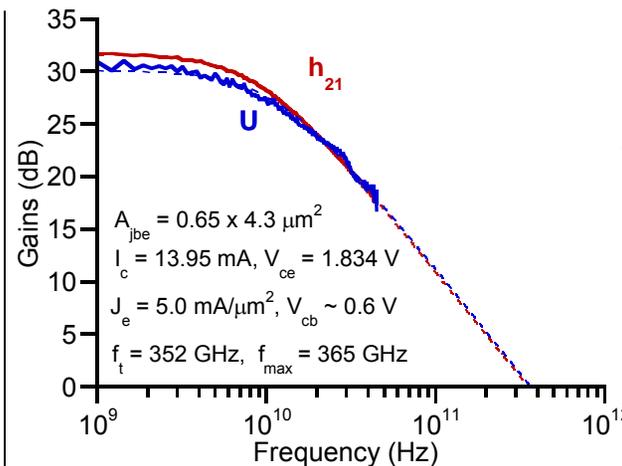
HBT with Epitaxial Extrinsic Emitter



Subcollector & Pedestal Implant



Subcollector implant eliminates C_{cb} in base pad area -key for high speed in lower-power logic. Pedestal further reduces C_{cb} .

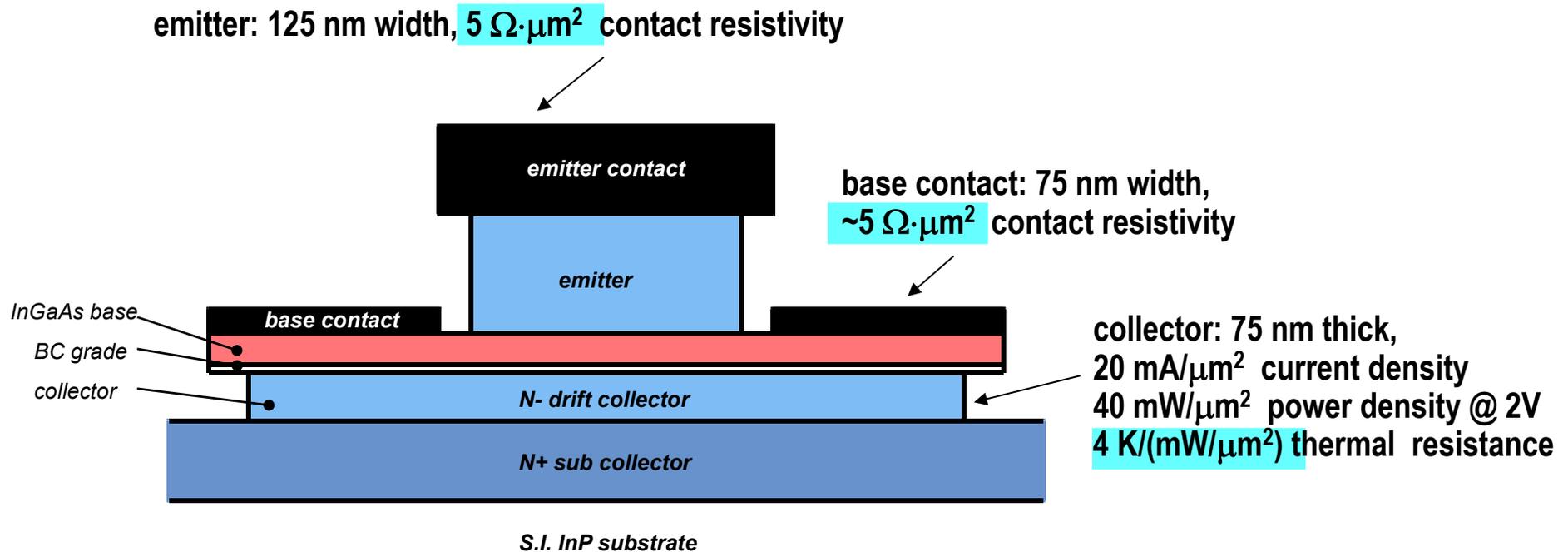


Roadmap for the 125 nm Scaling Generation

Target transistor performance: 700 GHz f_{τ} , 1100 GHz f_{\max} ,
comparable improvement of other key parameters: $C_{cb}\Delta V/I_c$, $R_{ex}I_c/\Delta V$, $R_{bb}I_c/\Delta V$

Target circuit performance
330 GHz digital clock rate (static dividers)
600 GHz power amplifiers

What would be needed to obtain this ?



Indium Phosphide HBTs for 100-600 GHz ICs

InP HBT now: at 500 nm scaling generation

455 GHz f_t & 485 GHz f_{max}

150 GHz static dividers & 180 GHz amplifiers demonstrated

200 GHz digital latches & 300 GHz amplifiers are feasible

InP HBT: future, at 125 nm scaling generation

2:1 increase in bandwidth (?)

700 GHz f_t & 1.1 THz f_{max} , 330 GHz digital latches & 600 GHz amplifiers ?

demands 4:1 better Ohmic contacts

demands 4:1 increased current density.

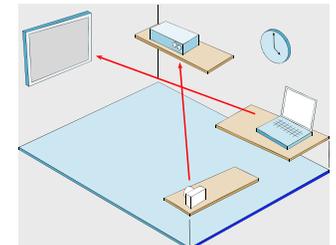
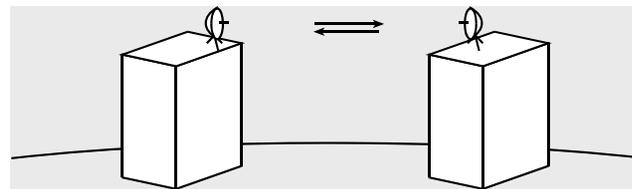
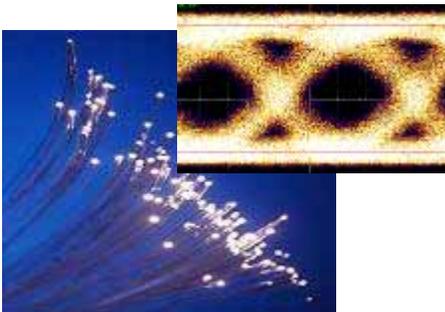
Applications:

160+ Gb/s fiber ICs,

300 GHz MIMICs for communications, radar, & imaging

GHz ADCs / DACs / DDFS / etc.

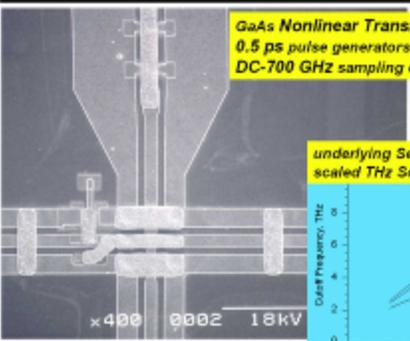
& applications unforeseen & unanticipated



Backups

Submicron diodes for sub-millimeter-waves

Scaled Schottky diodes ICs for near-THz Instruments



GaAs Nonlinear Transmission Line ICs:
0.5 ps pulse generators &
DC-700 GHz sampling circuits

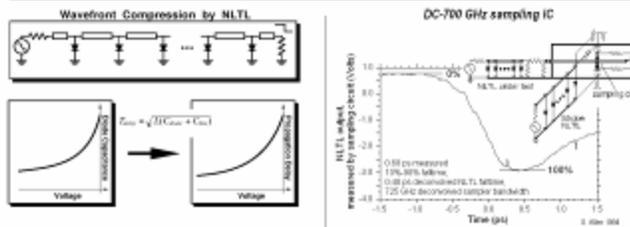
underlying Semiconductor Technology:
scaled THz Schottky varactor diodes

0.5 μm design rules

1st monolithic NLTLs: Rodwell, Madden, & Bloom, 1986
Stanford, UCSB, Hewlett-Packard -1985-1995

Instrumentation, not communication technology:
NLTL harmonic conversion loss $\sim 1/m^2$, noise figure of sampling

NLTL-gated diode sampling ICs: results from the 1990's



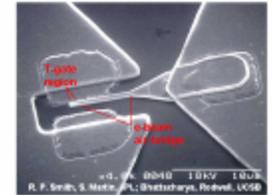
Wavefront Compression by NLTL

DC-700 GHz sampling IC

mm-wave on-wafer network analysis

mm-wave spectrometer

Deep submicron diode ICs for (sub)-mm-wave applications



Scaled Schottky mixer diodes

Submicron Schottky-Anode Resonant-Tunnel-Diodes

$$f_{max} = (2\pi)^{-1} (R_s C)^{-1/2} (R_s C)^{-1/2} f_{ph}^{-1/2} \rightarrow 2 \text{ THz}$$

RTD Scaling:
reduce contact width: 0.1 μm
reduce depletion depth: 300 Å
increase J: $5 \cdot 10^6 \text{ A/cm}^2$
use zero-resistance top Schottky contact

04-element Schottky-RTD oscillator at 650 GHz

array oscillator

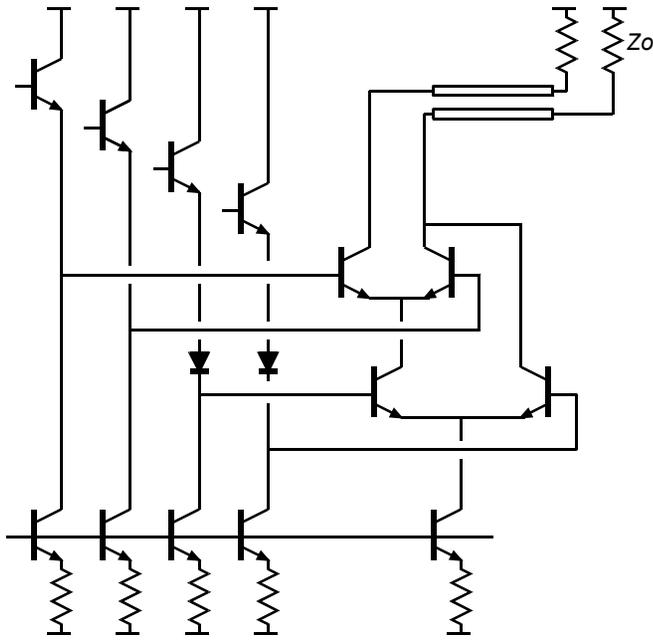
SRTD slot oscillator

0.1 μm, 2.2 THz Schottky-RTD

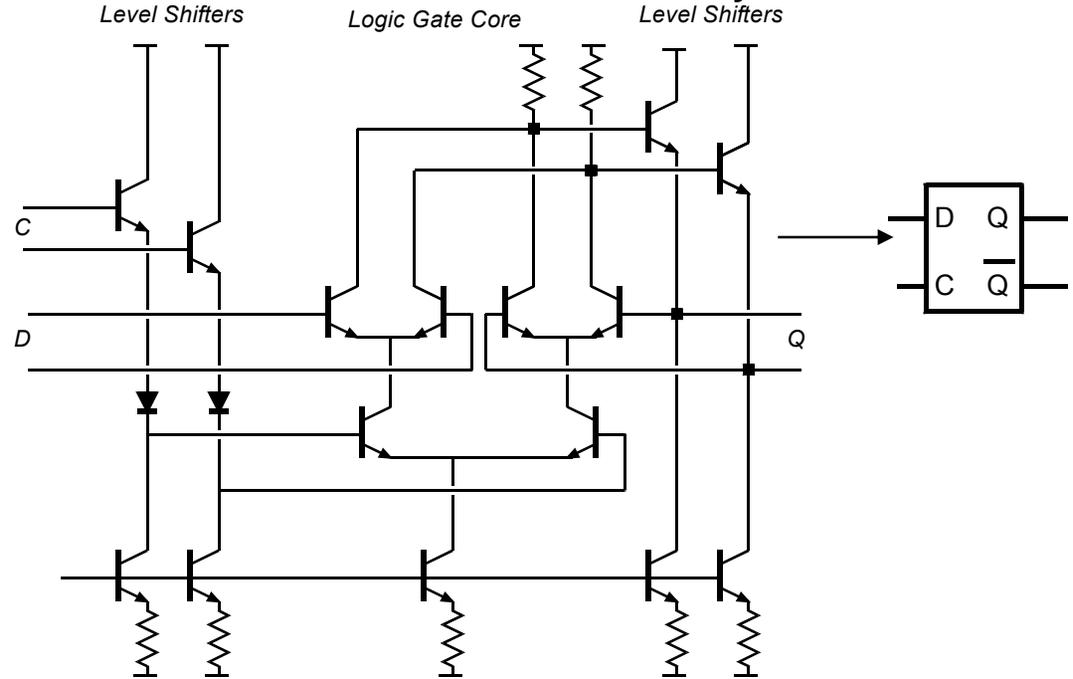
Low power: 20 μW from 60 dBmward 200 GHz array, extremely low efficiency.
RTDs are a single-application device with limited general utility.

Hierarchy of ECL Static Frequency Divider

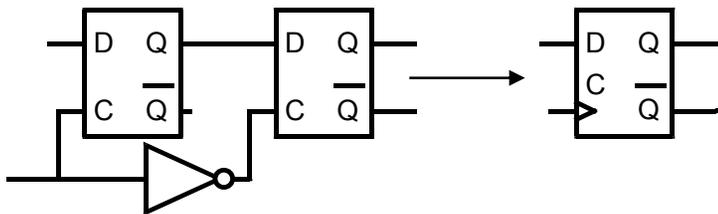
ECL NAND/NOR Gate



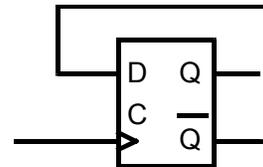
ECL Latch: level-clocked memory element



Master-Slave Latch: transition-clocked memory element



2:1 Static Frequency Divider

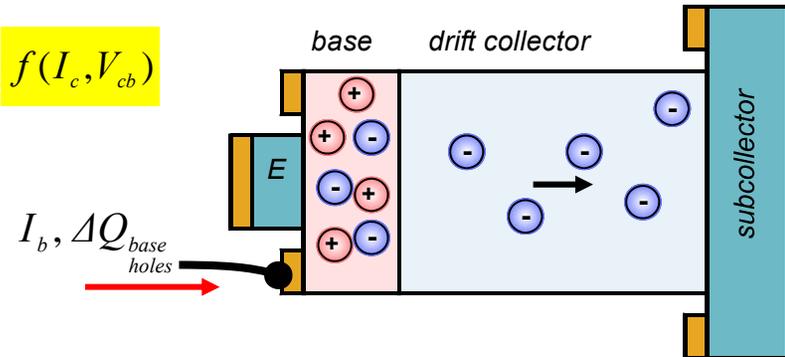


Transit time Modulation Causes C_{cb} Modulation

$$Q_{base\ holes} = \cancel{\text{constant}} + \cancel{Q_{base\ electrons}} + \int_0^T qn(x)A(1-x/T_c)dx + V_{bc}\epsilon A/T_c = f(I_c, V_{cb})$$

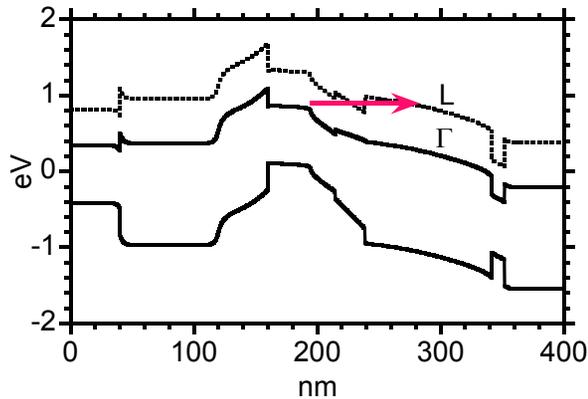
$$C_{cb} \equiv -\frac{\partial Q_{base\ holes}}{\partial V_{cb}} \quad \tau_f \equiv \frac{\partial Q_{base\ holes}}{\partial I_c} \Rightarrow \frac{\partial C_{cb}}{\partial I_c} = -\frac{\partial \tau_f}{\partial V_{cb}}$$

Carnitz and Moll, Betser & Ritter, D. Root



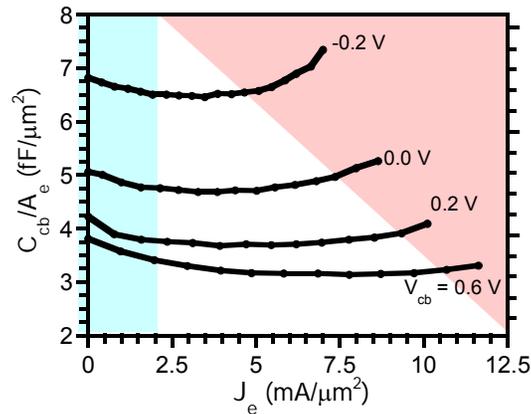
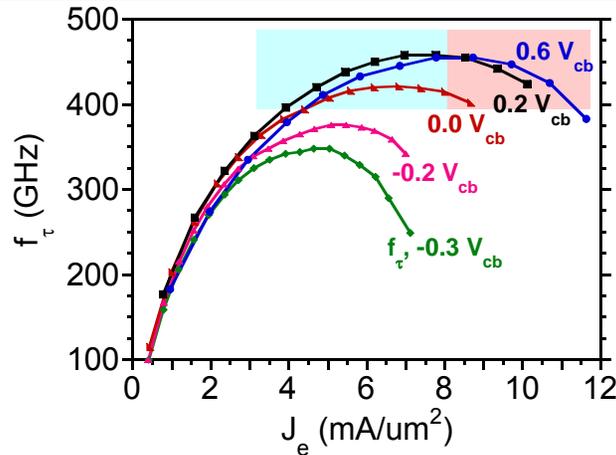
Collector Velocity Modulation :

$$\partial \tau_f / \partial V_{cb} > 0 \Rightarrow \partial C_{cb} / \partial I_c < 0$$



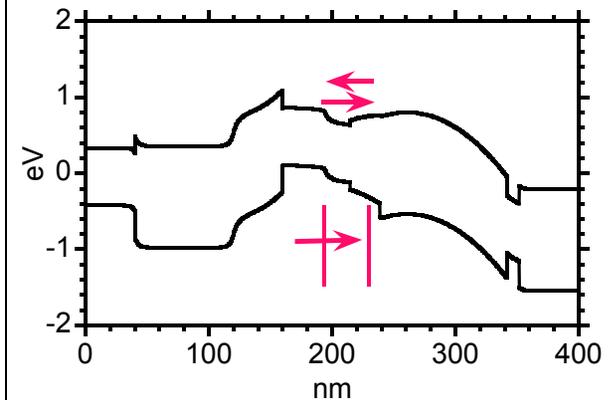
Increase in τ_c with $V_{cb} \rightarrow$ reduced C_{cb}

- strong effect in InGaAs SHBTs
- weak effect in InP DHBTs



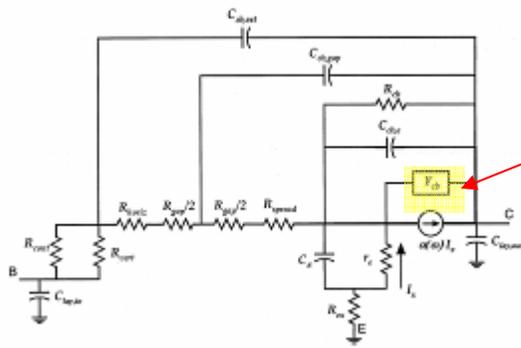
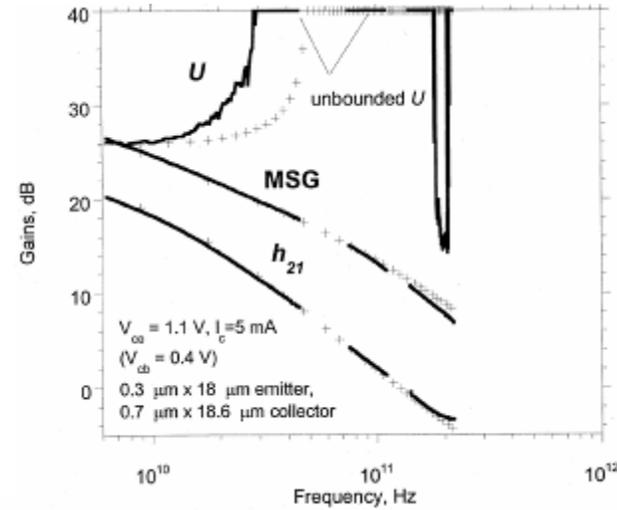
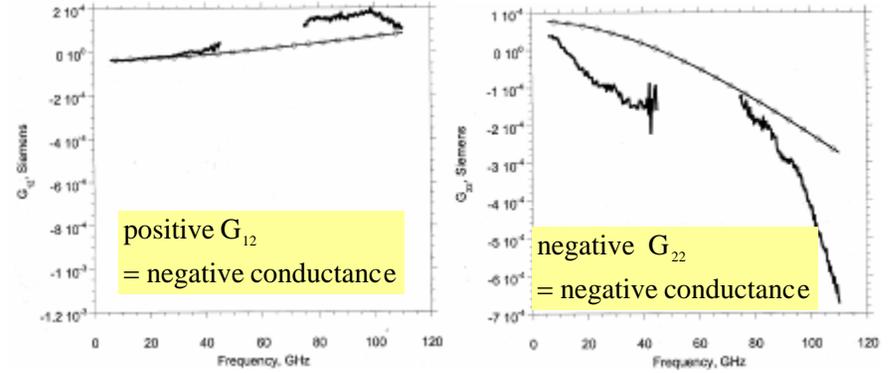
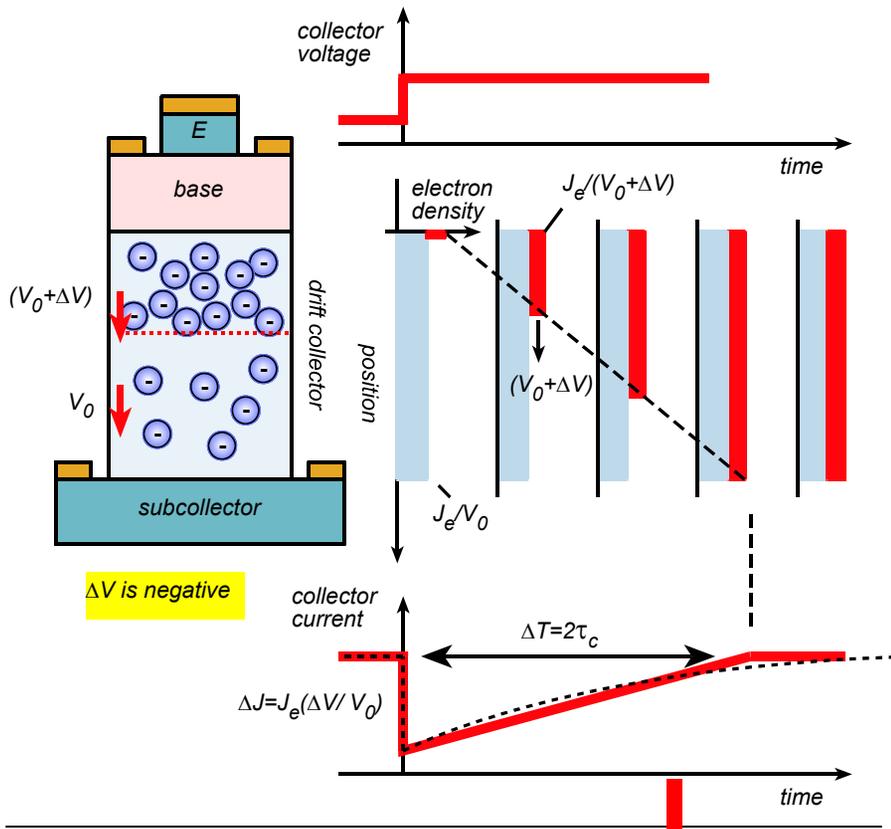
Kirk Effect :

$$\partial \tau_f / \partial V_{cb} < 0 \Rightarrow \partial C_{cb} / \partial I_c > 0$$



- Increase in C_{cb} is due to both
- base pushout into collector
 - and modulation of τ_b by V_{cb}

Transit time Modulation → Negative Resistance → Infinite Gain



negative capacitance

$$C_{cb,canc} = -I_c (\partial \tau_f / \partial V_{cb})$$

negative resistance

$$R = 2(\tau_c / 3C_{cb,canc})$$

